

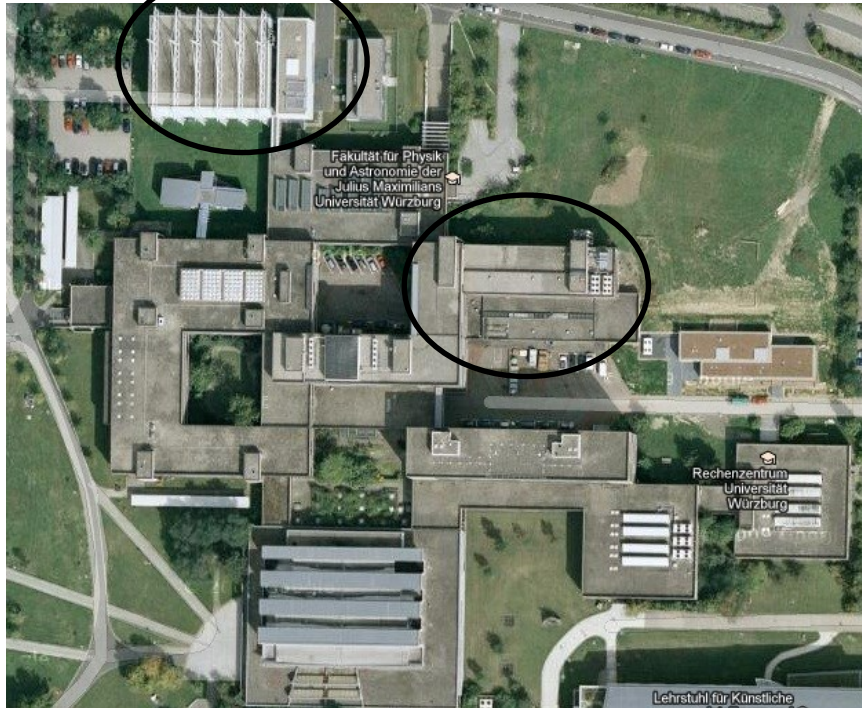
# Nano-electronic Stochastic Logic Gates - Memory Devices - Sensors and Energy Harvester

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Wilhelm Conrad Röntgen Research Center for Complex Material  
Systems*

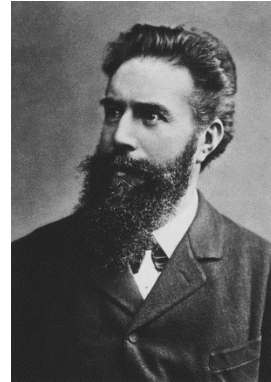
*<sup>2</sup>NiPS Laboratory, Dipartimento di Fisica, Università di Perugia*

Department of physics and astronomy



Source: [google.de/maps](http://google.de/maps)

8 experimental physics chairs  
5 theoretical physics chairs  
+ several experimental and theoretical  
work groups



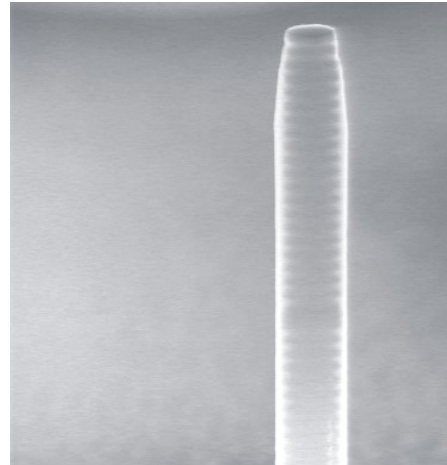
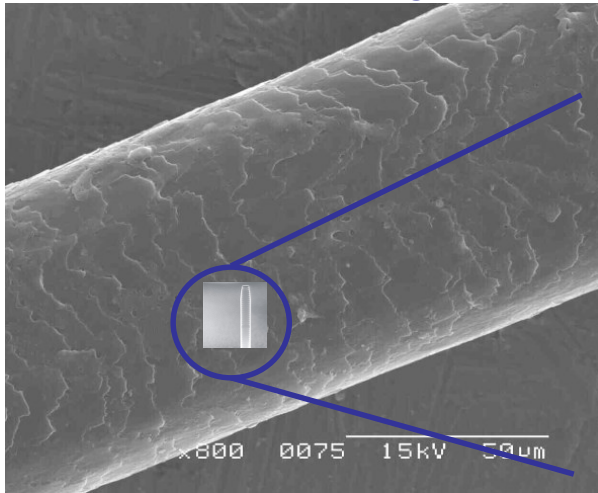
**Wilhelm C. Röntgen**  
First Nobel Prize 1901  
(X-rays)

**Klaus von Klitzing**  
Nobel Prize 1985  
(Quantum Hall effect)

Other nobel laureates with a  
Würzburg history:

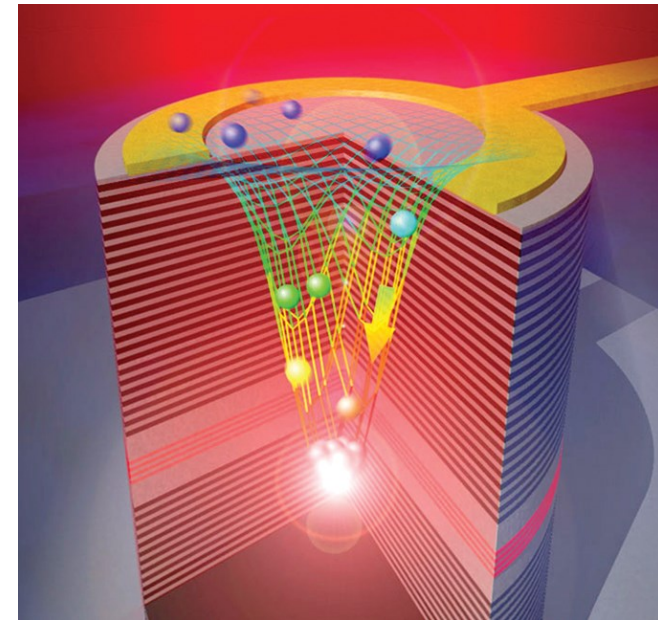
- Wilhelm Wien, Johannes Stark, Svante Arrhenius, Ferdinand Braun, Max von Laue, “Werner Heisenberg”

## Quantum electrodynamics



J.P. Reithmaier et al., „Strong coupling in a single quantum dot–semiconductor microcavity system“, *Nature* **432**, 197-200 (11 November 2004).

## Polariton laser



"An electrically pumped polariton laser"  
C. Schneider et al., *Nature* 497, 348–352 (2013).

## Mars Exploration Rover Mission



Picture: Courtesy of NASA/JPL - Caltech

[http://www.nanoplus.com/index.php?option=com\\_content&view=article&id=78](http://www.nanoplus.com/index.php?option=com_content&view=article&id=78)

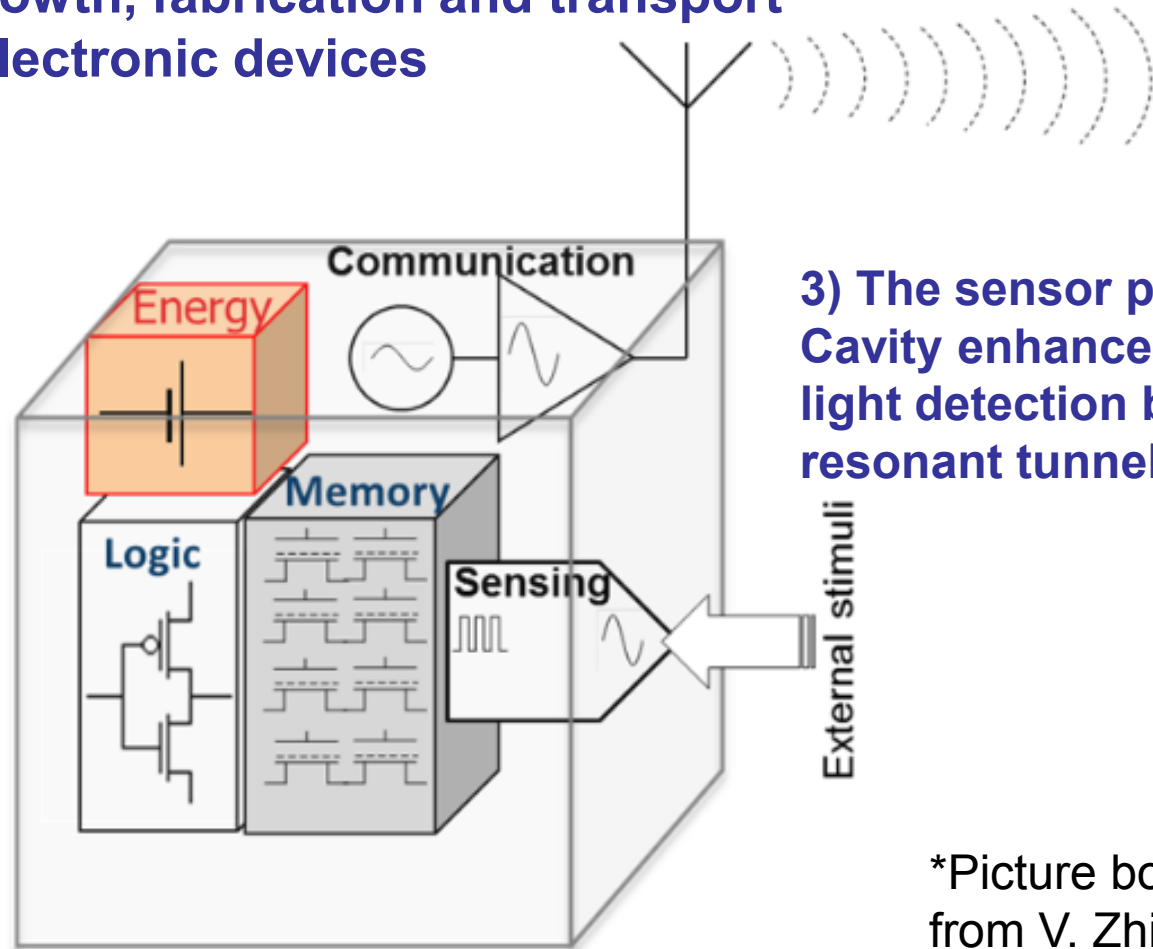
**0) The intro part: Growth, fabrication and transport properties of nanoelectronic devices**

**4) The energy harvester part: Voltage fluctuation to current conversion**

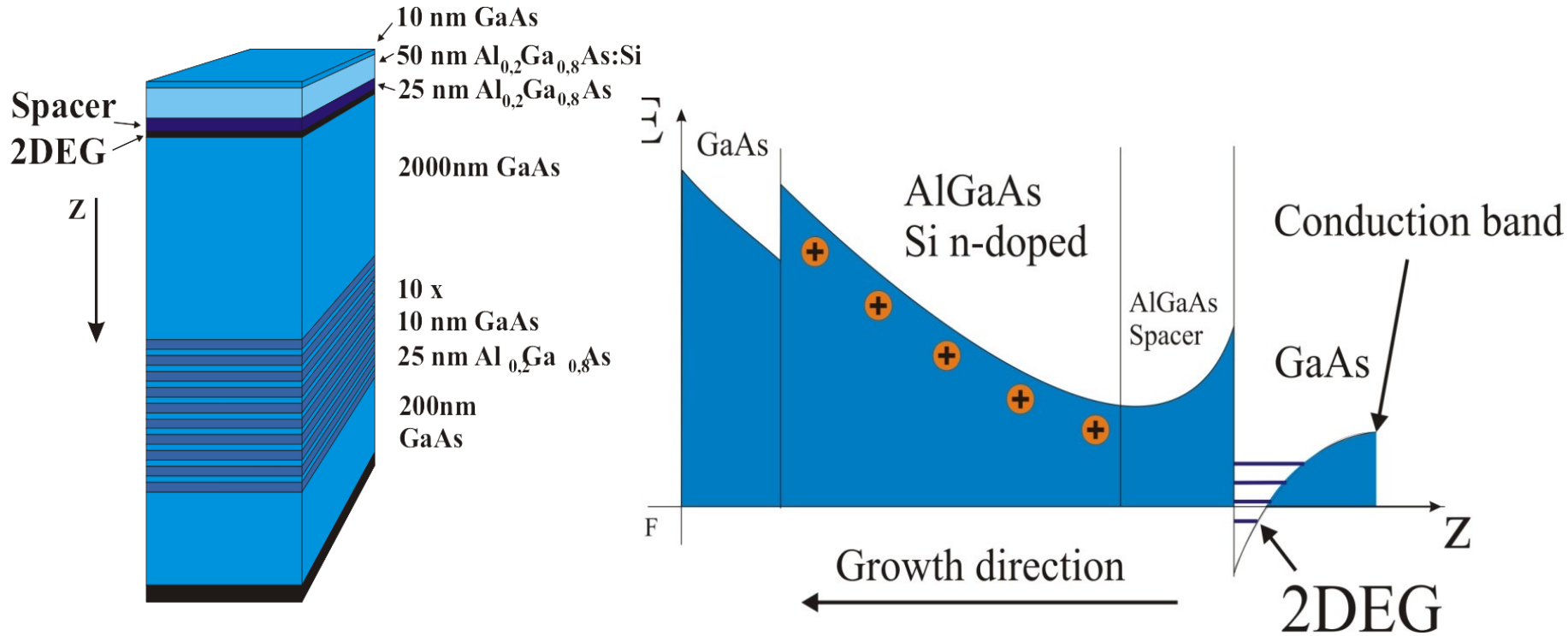
**1) The logic gate part: Stochastic universal logic gates**

**2) The memory part: Quantum dot floating gate transistor**

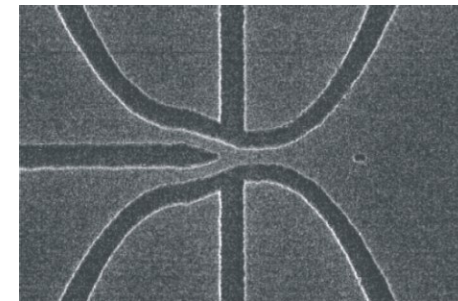
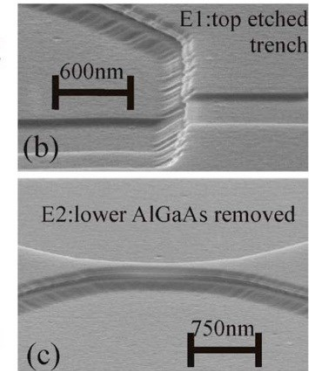
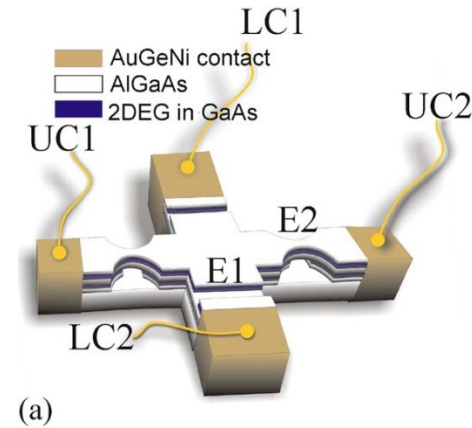
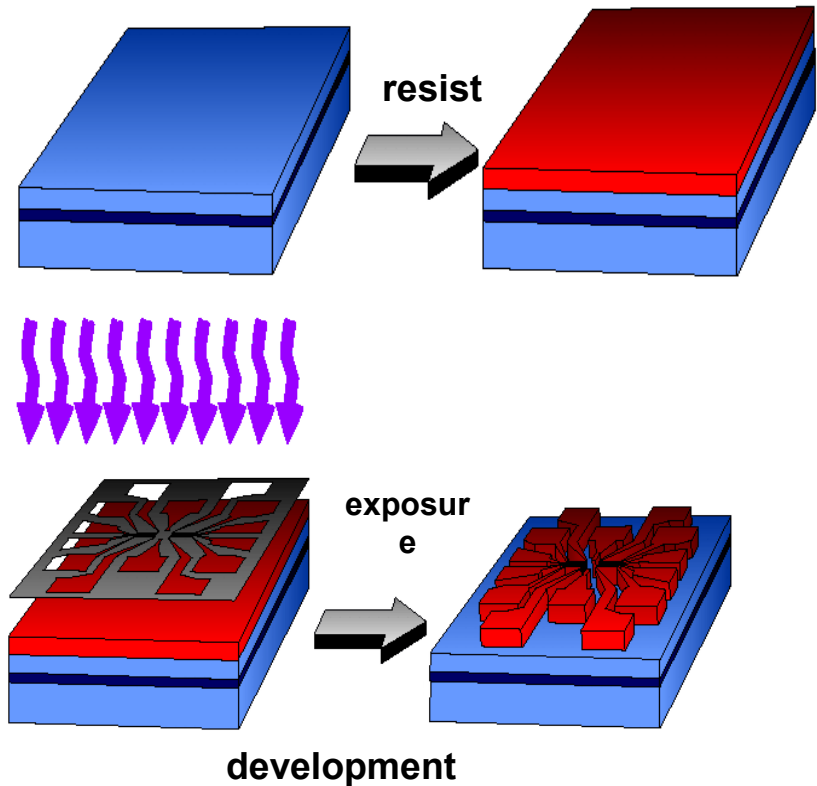
**3) The sensor part: Cavity enhanced light detection by resonant tunneling**



\*Picture borrowed from V. Zhirnov's talk

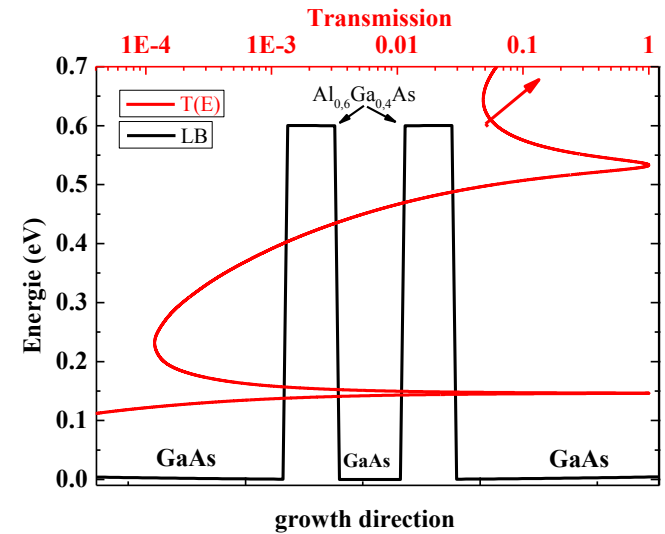
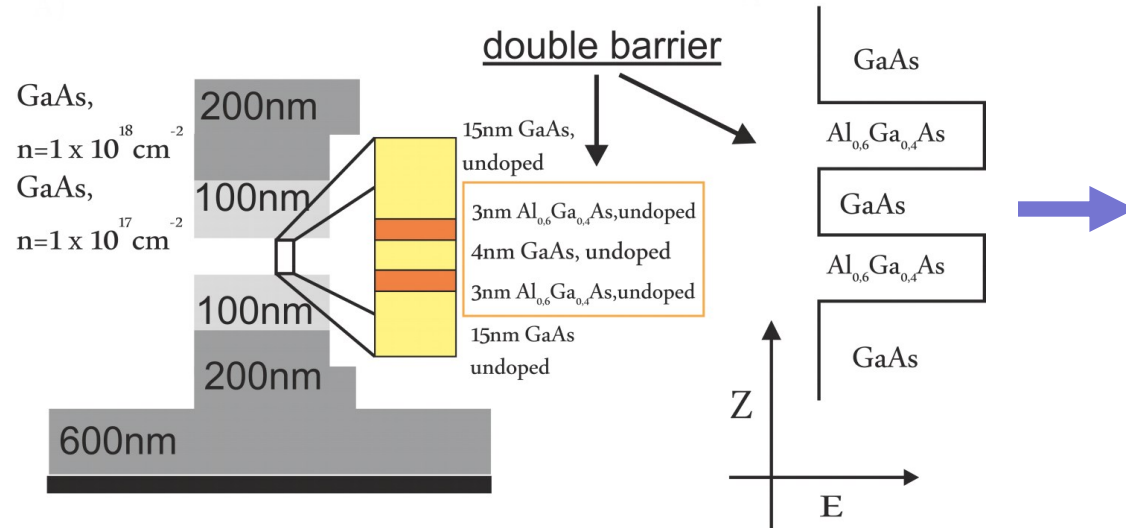


- ➔ Modulation doped GaAs/AlGaAs heterostructure.
- ➔ Grown by molecular beam epitaxy.
- ➔ High mobility  $\mu = 1.1 \cdot 10^6 \text{ cm}^2/\text{Vs}$  and charge density  $n = 3.7 \cdot 10^{11} \text{ cm}^{-2}$ .

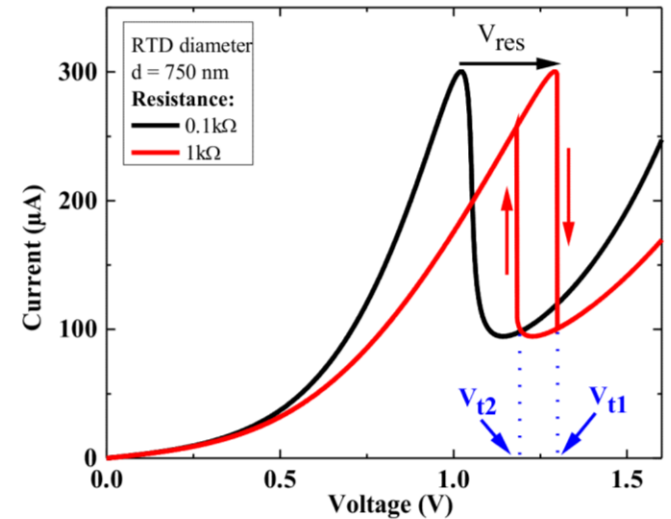
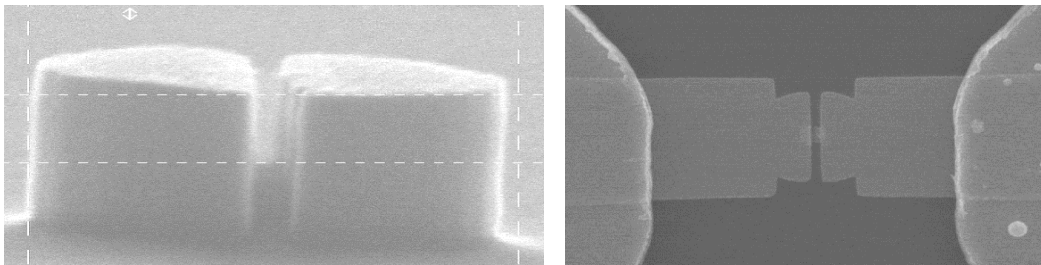


- Electron beam or optical lithography.
- Wet or dry chemical etching (e.g. ECR-RIE).

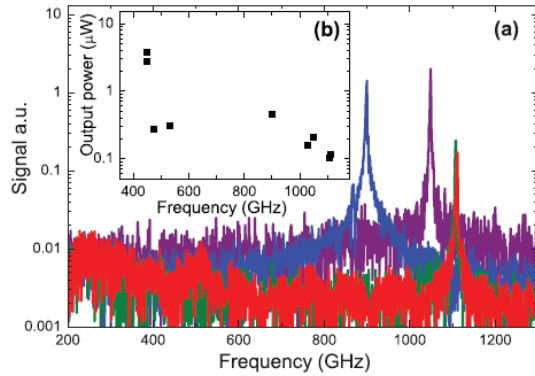
## GaAs based RTDs with AlGaAs barriers.



## Trench etched RTD

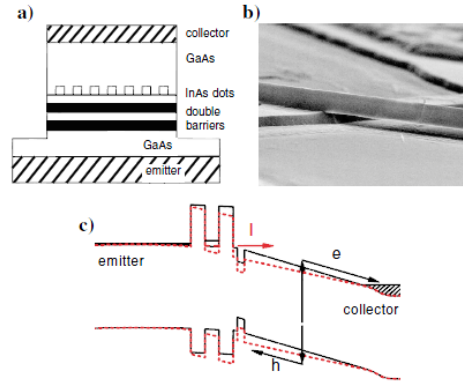


## Oscillator



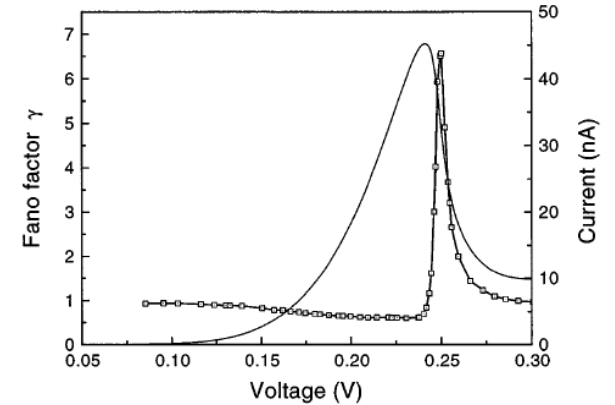
Feiginov et al., Appl. Phys. Lett. **99**, 233506 (2011).

## Photosensor



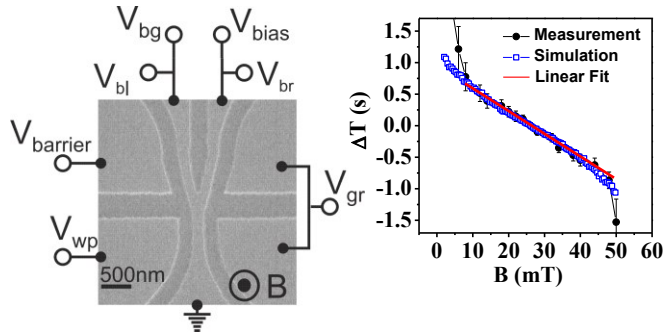
J. C. Blakesley, et al., PRL **94**, 067401 (2005).

## Noise correlation



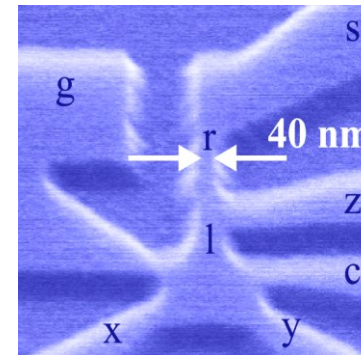
G. Iannaccone et al., PRL **80**, 1054-1057 (1998).

## Noise activated nonlinear dynamical sensor



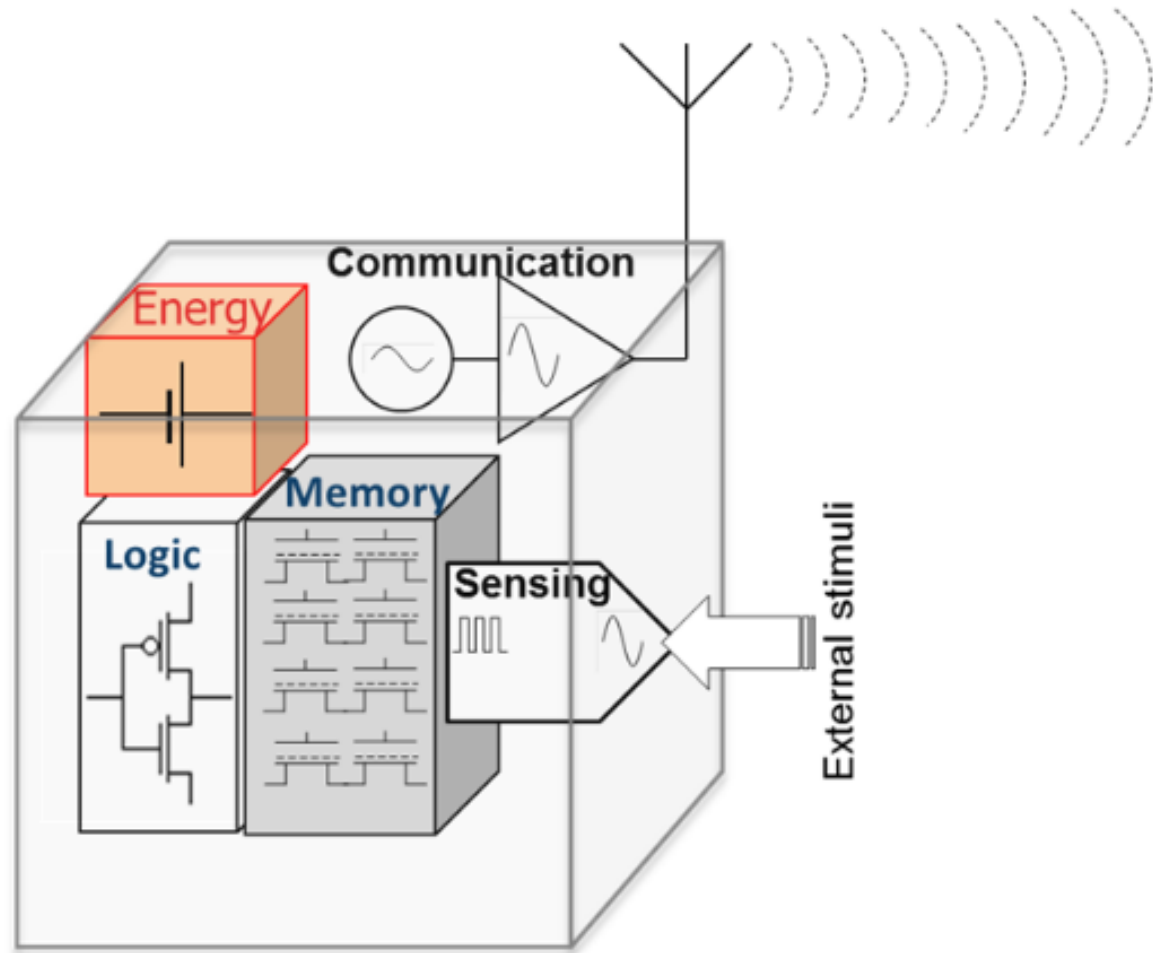
F. Hartmann et al, Appl. Phys. Lett. **96**, 082108 (2010).

## Half and full adder



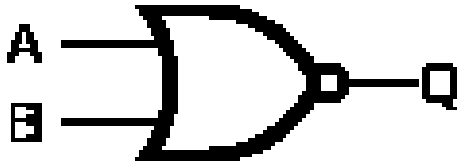
B. Lau, D. Hartmann, L. Worschech and A. Forchel, IEEE Transactions on Electron Devices **53**, 1107 (2006)





1) The logic gate part:  
Stochastic universal  
logic gates

**NOR gate:**

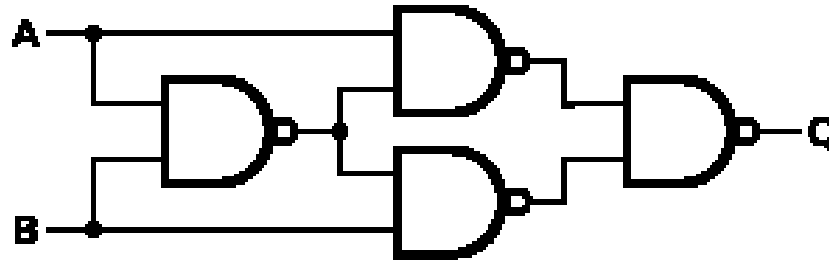


**Truth table:**

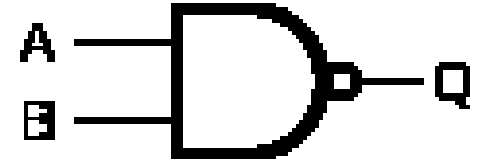
A	B	Q
0	0	1
1	0	0
0	1	0
1	1	0

**XOR gate  
(binary sum):**

A	B	Q
0	0	0
1	0	1
0	1	1
1	1	0



**NAND gate:**

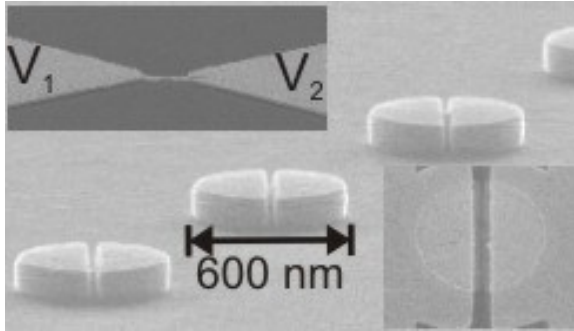


**Truth table:**

A	B	Q
0	0	1
1	0	1
0	1	1
1	1	0

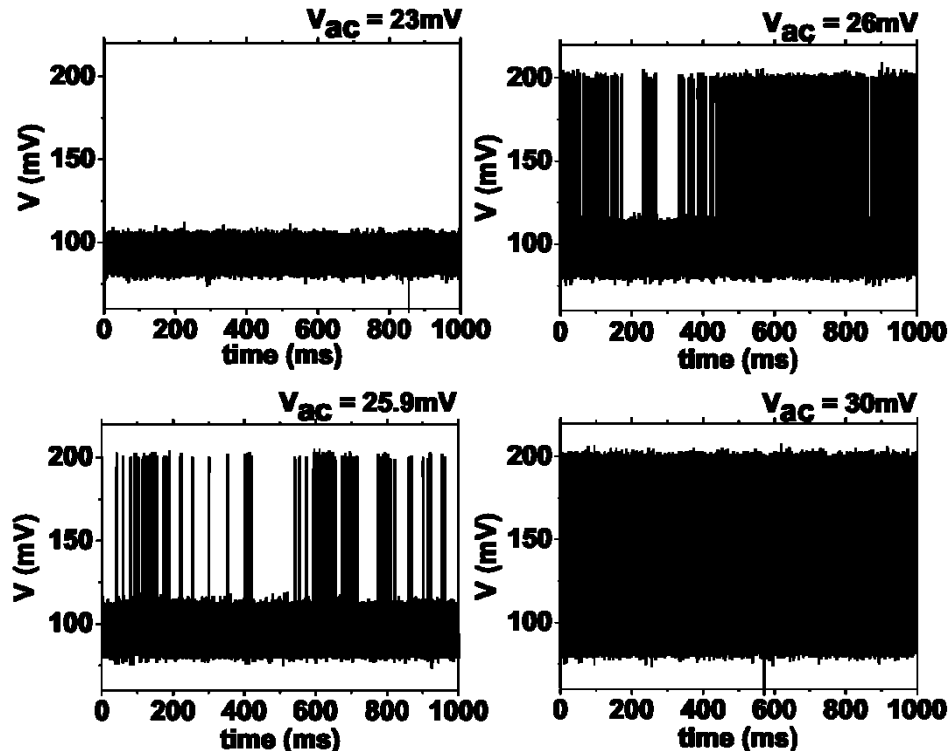
**Universal logic gate:**

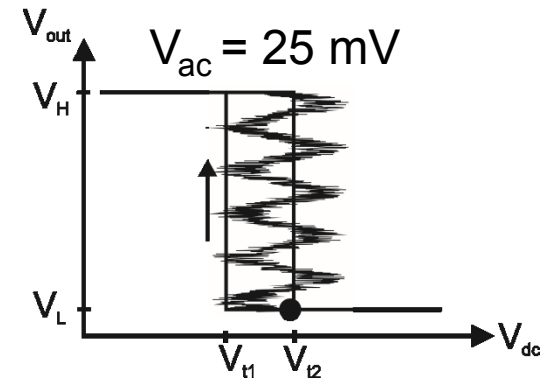
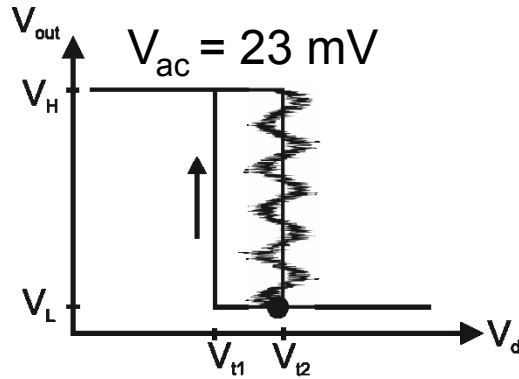
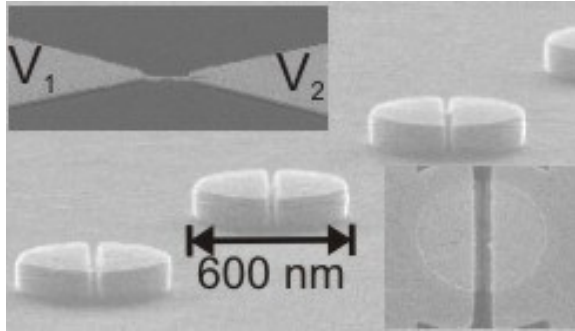
- Any logic gate can be made from a combination of NAND or NOR gates.



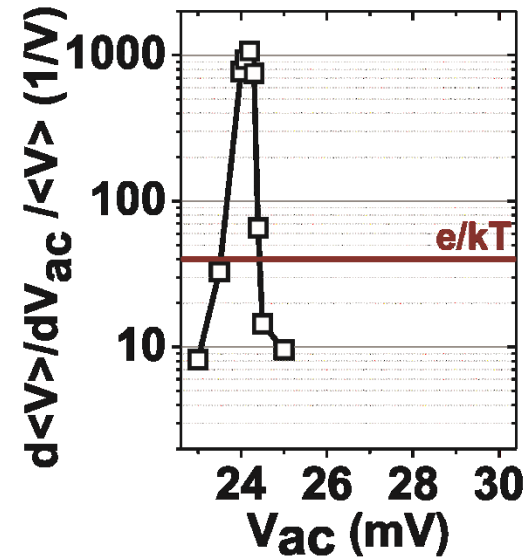
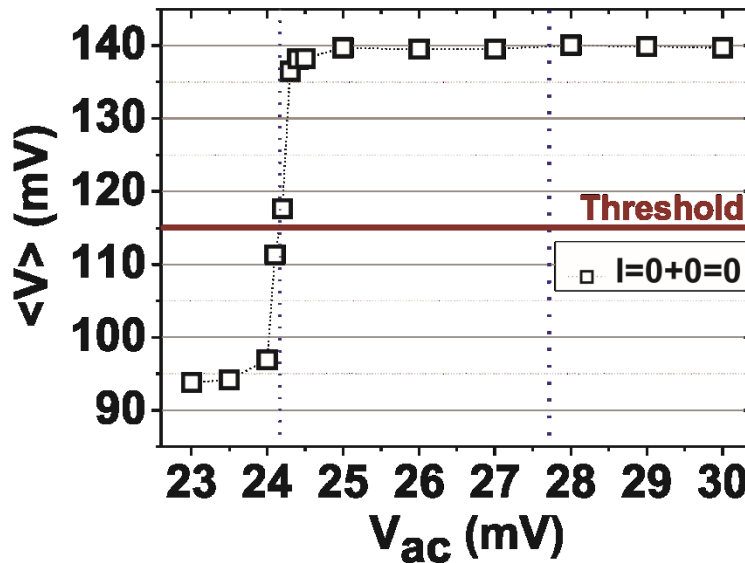
- Electron microscopy images of a trench etched RTD with diameter  $d = 600 \text{ nm}$
- Branches serve as logical inputs

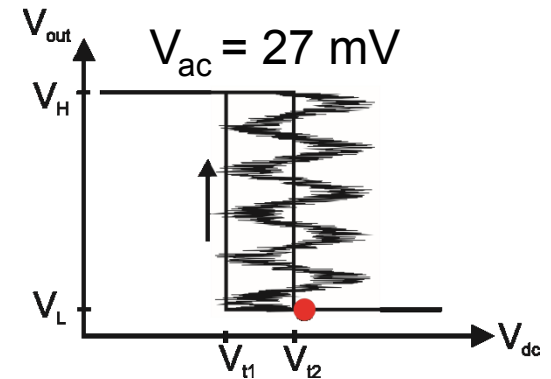
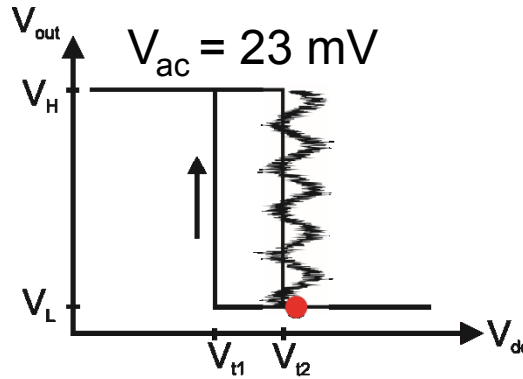
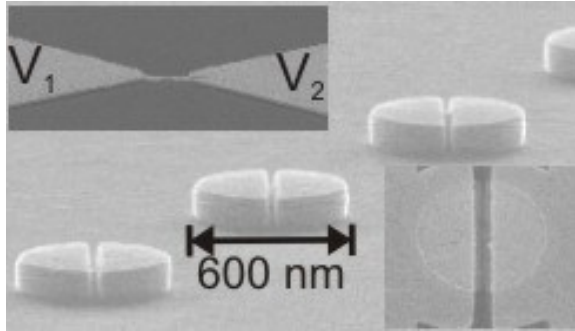
- Noise induced signal trains
- Mean value is efficiently controlled by input signals
- Can be integrated to arrays
- No classical  $kT$  limit of transconductance



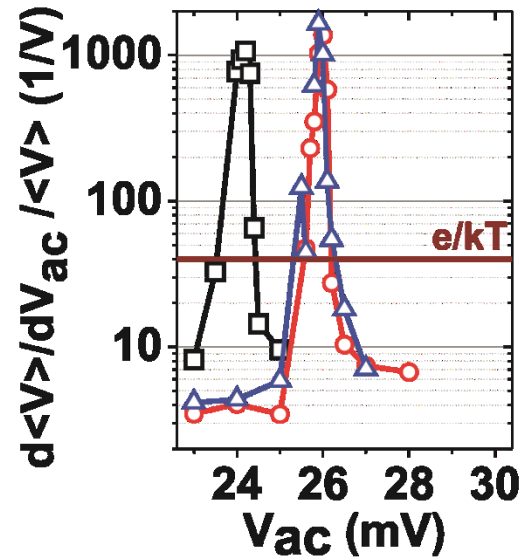
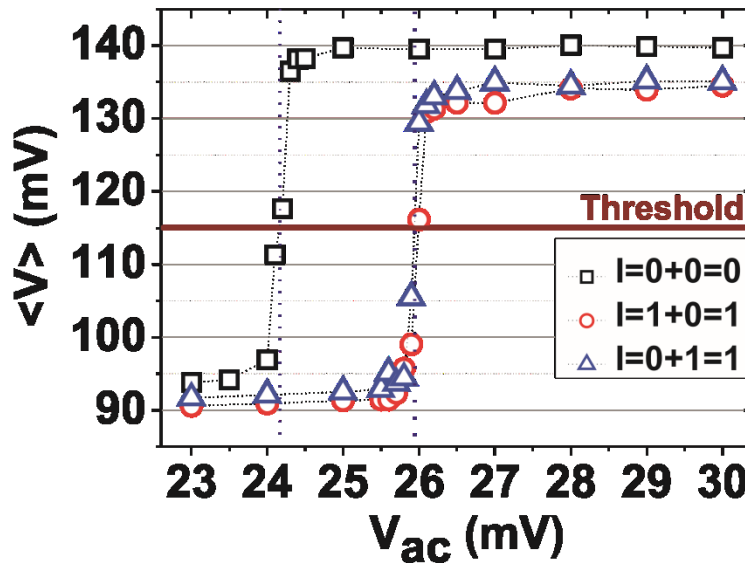


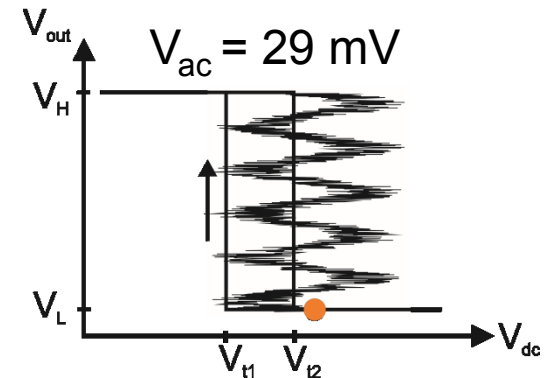
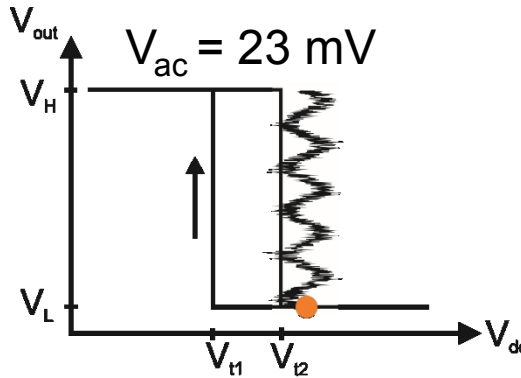
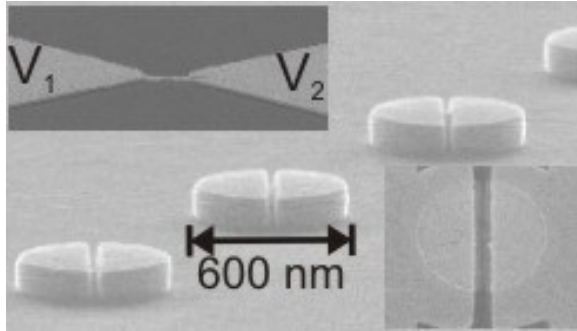
Switching voltages:  $V_1 = V_2 = 0\text{mV}$



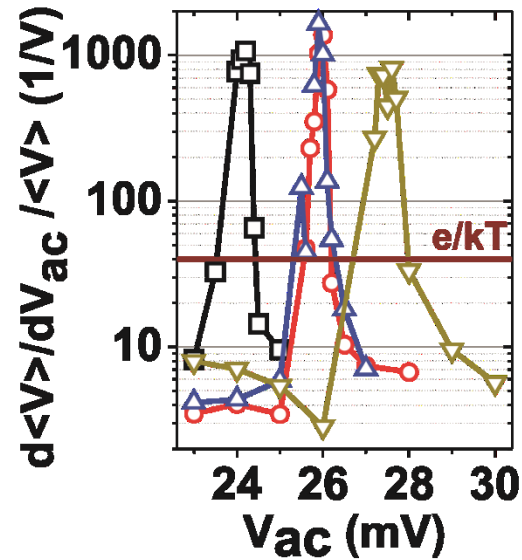
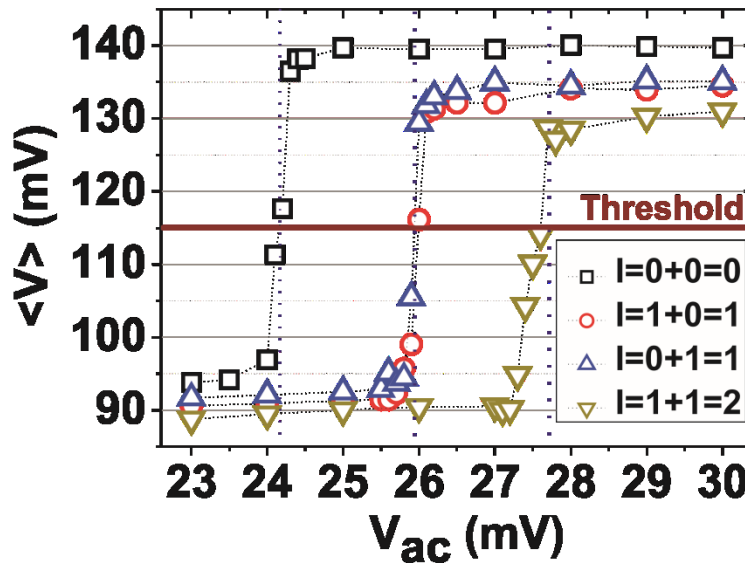


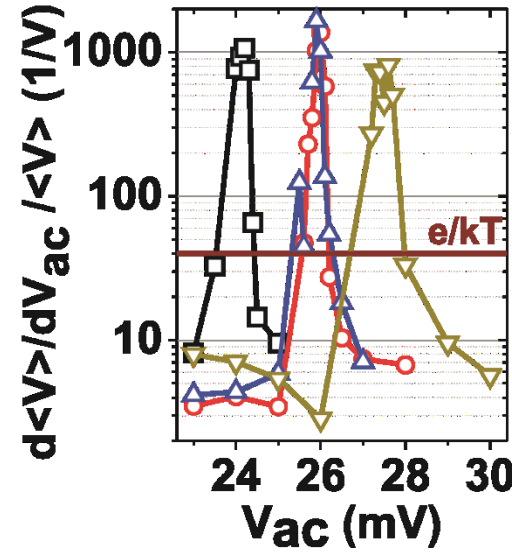
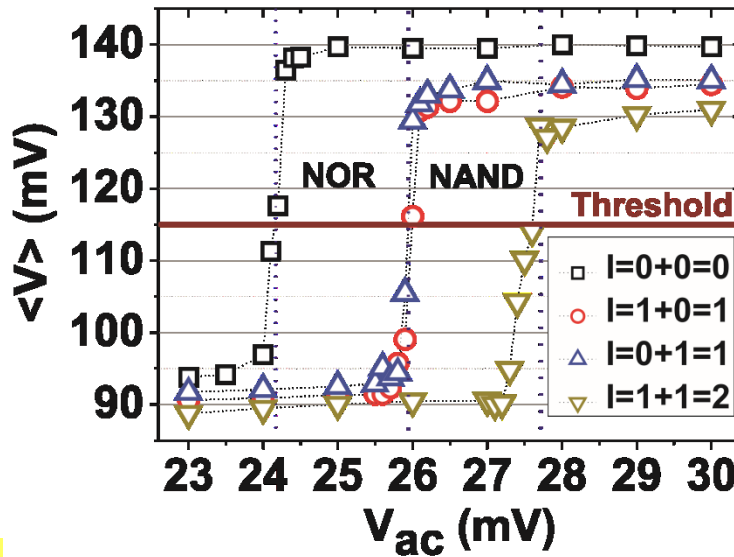
Switching voltages:  $V_1 = 0, 2 \text{ mV}$   $V_2 = 2, 0 \text{ mV}$





Switching voltages:  $V_1 = V_2 = 2$  mV





NOR

0	0		1
1	0		0
0	1		0
1	1		0

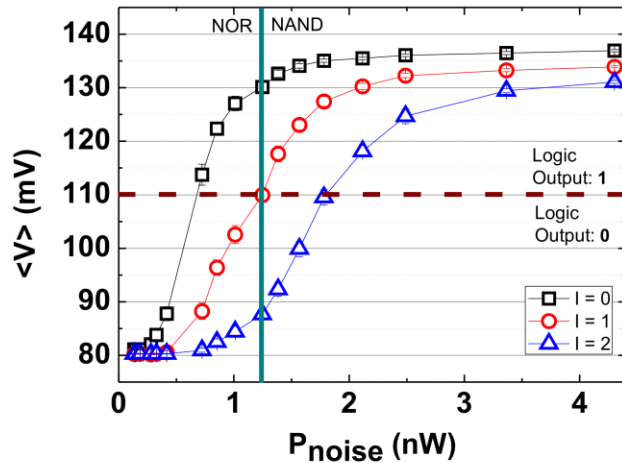
NAND

0	0		1
1	0		1
0	1		1
1	1		0

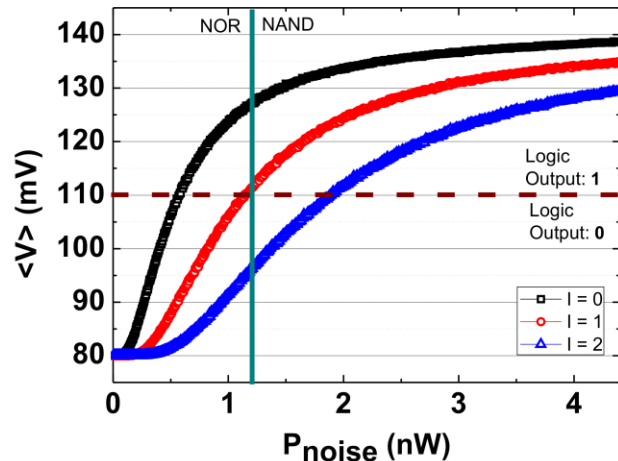


□ Switch from NOR to NAND for  $\Delta V_{ac} < 1$  mV with a logic input voltage 2 mV

## experiment



## simulation



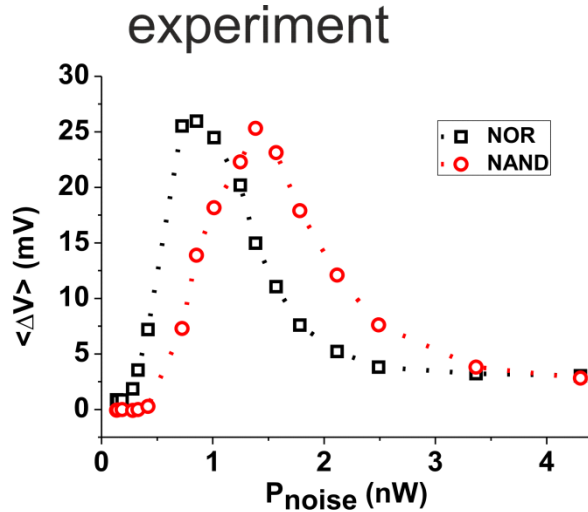
## Previous:

- Universal logic gate switching controlled the amplitude of the periodic forcing.

## Now:

- Universal logic gate switching solely controlled by the noise floor.
- Two universal logic gates: NOR/NAND.
- Switching between the gates only as a function of noise power.





## For the logic NOR gate:

- The mean value difference is defined as

$$\langle V \rangle = V(I=0) - V(I=1)$$

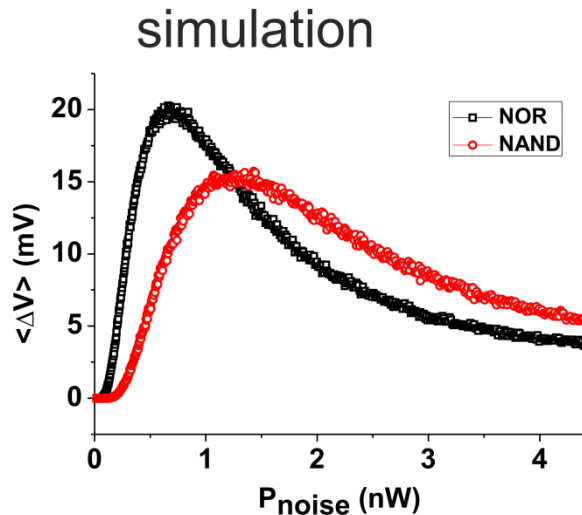
$P_{\text{noise}} = 0.9 \text{ nW}$  the maximum corresponds to the logic NOR

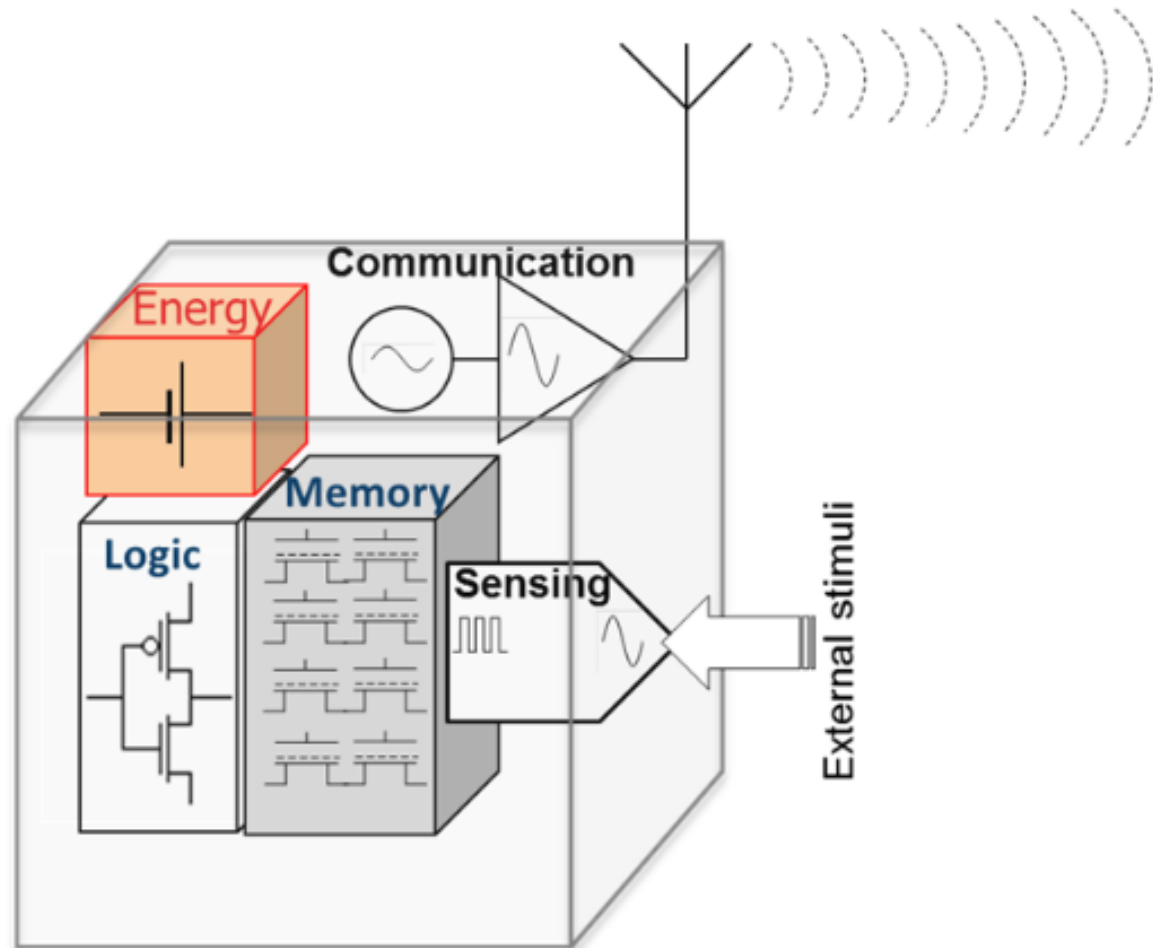
## For the logic NAND gate:

- The mean value difference is defined as

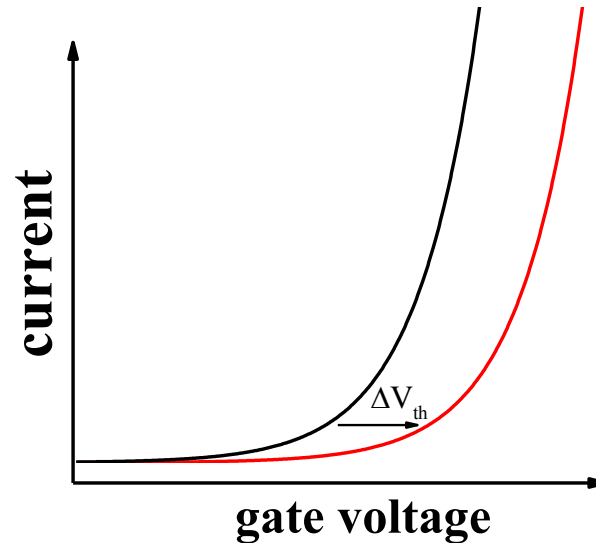
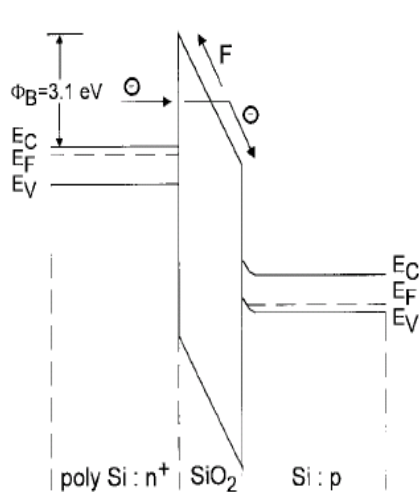
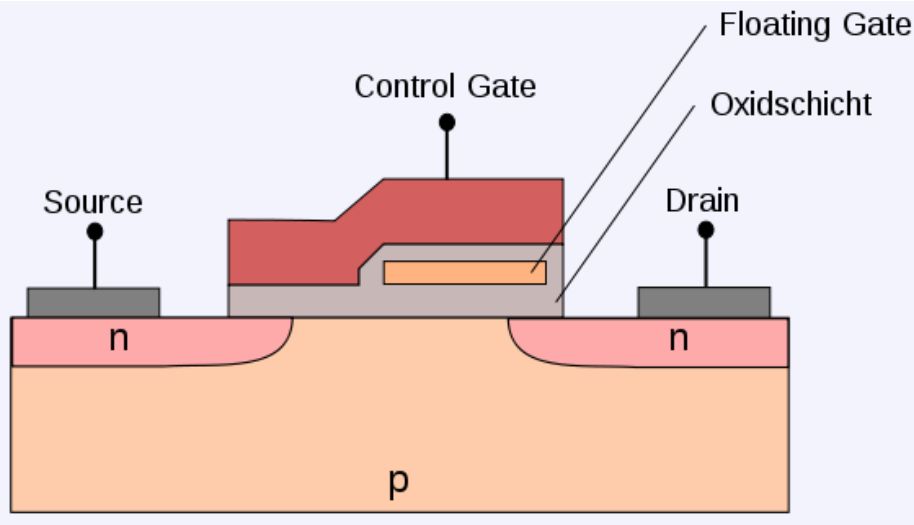
$$\langle V \rangle = V(I=1) - V(I=2)$$

$P_{\text{noise}} = 1.4 \text{ nW}$  the maximum corresponds to the logic NAND





## 2) The memory part: Quantum dot floating gate transistor



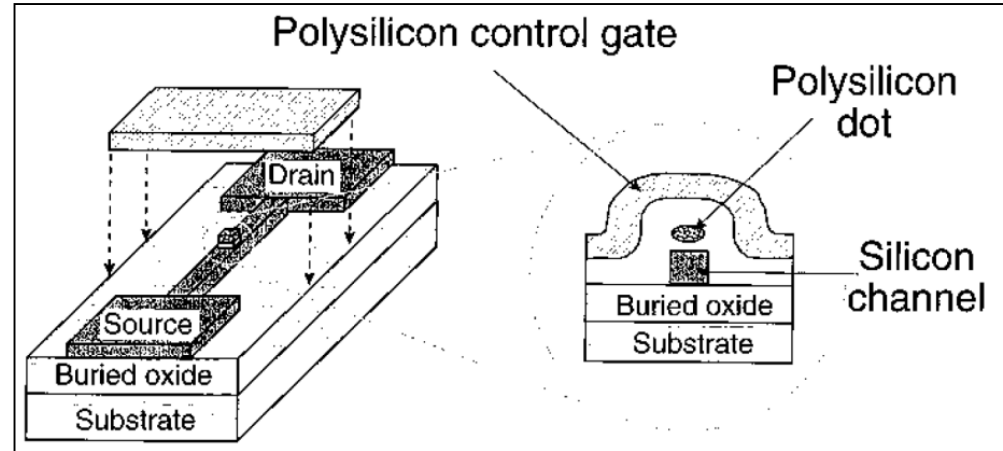
## Floating gate transistor:

- Non-volatile memory having a retention time of more than 10 years.
- A floating gate in a metal-oxide semiconductor field effect transistor (MOSFET) acts as the storage unit.
- SiO<sub>2</sub> barriers with an energetic height of 3.2 eV.

## Threshold voltage shift:

$$\rightarrow \Delta V_{th} = \frac{\Delta Q}{C_{eff}}$$

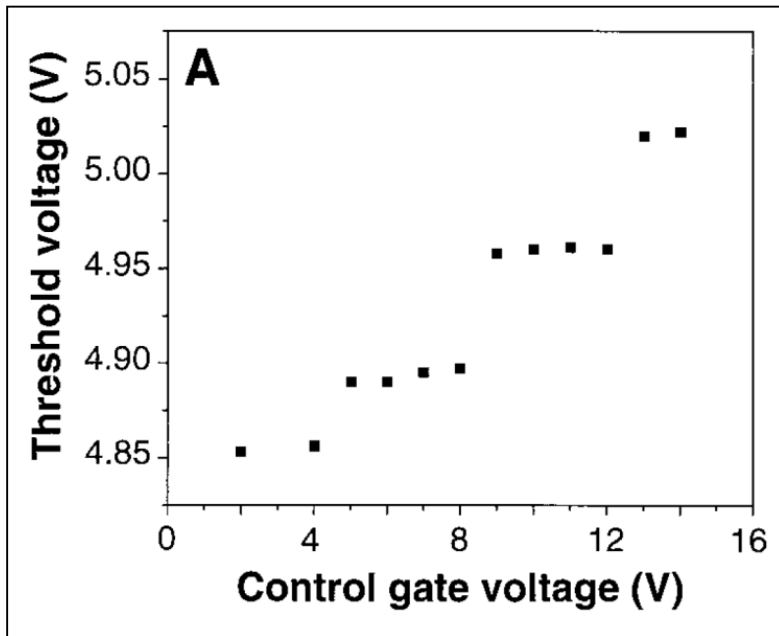
Demonstration of working principle of a 'silicon single-electron memory transistor'.



L. Guo et al., Science 275, 649 (1997)

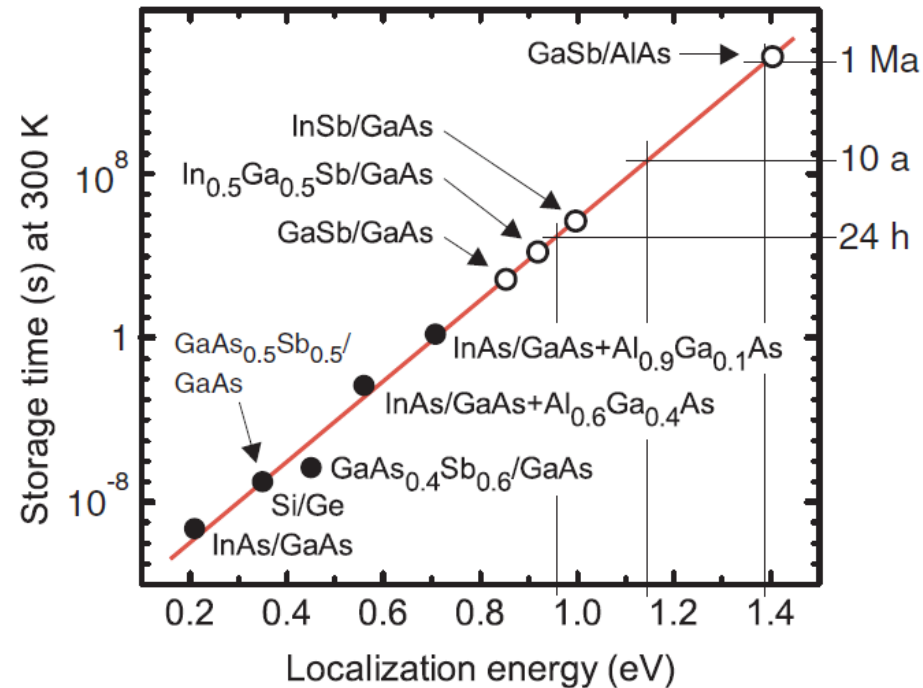
**Discrete** shift of threshold voltage in dependence on the number of stored electrons on the dot with

$$V_{th,up} = \frac{ne}{C_{dg}}$$



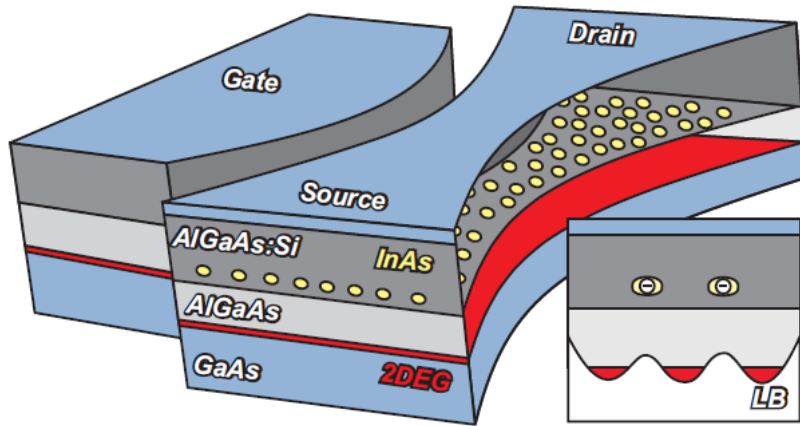
## Advantages compared to Si/SiO<sub>2</sub> system:

- The height of the barrier can be designed.
- Defect-free interfaces.
- Writing or erasing the device does not damage the structure.
- Hole-based charge storage can be used.



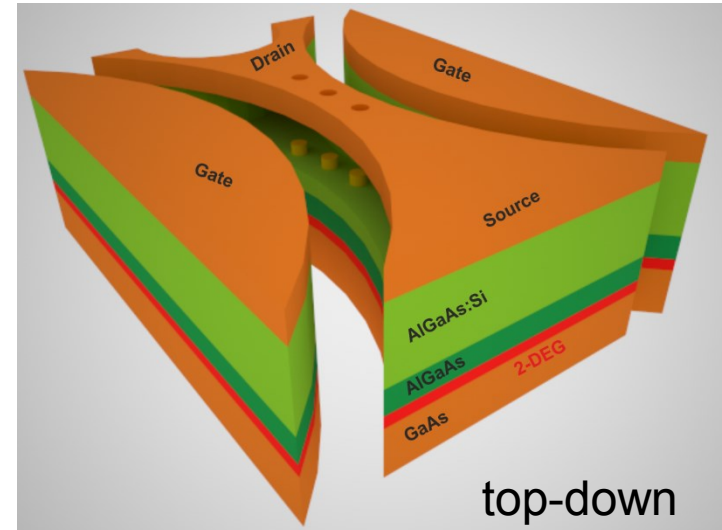
A. Marent et al., *Semicond. Sci. Technol.*  
**26** (2011) 014026

## QD-Flash memory with self-assembled QDs:



bottom-up

## QD-Flash memory with positioned site-controlled QDs:

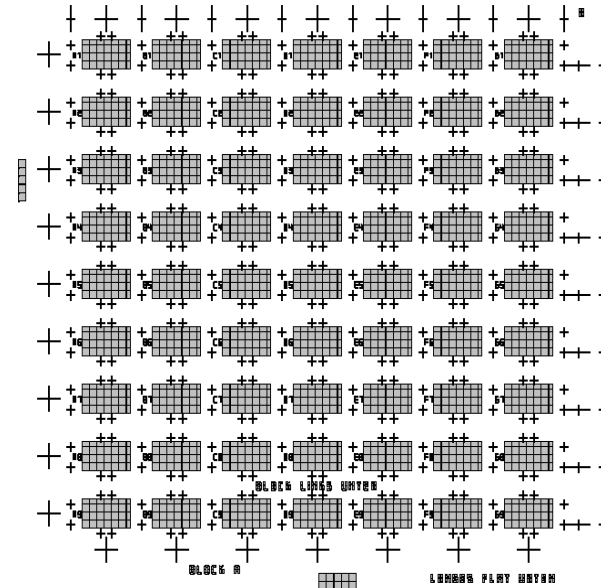
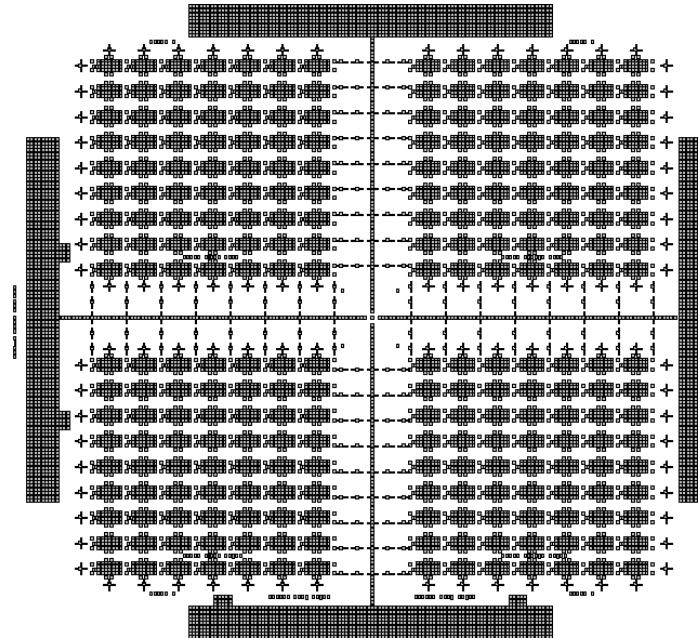
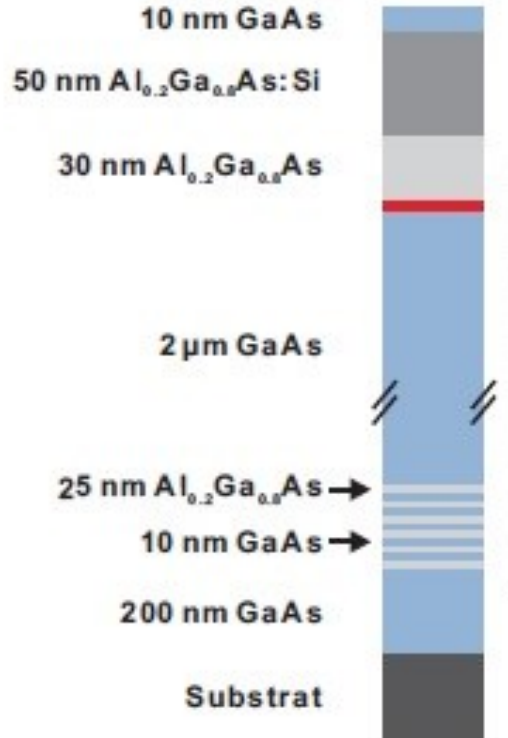


top-down

- Self-assembled QDs are randomly distributed.
- Charging of several QDs contribute to the threshold voltage shift.
- Ensembles of QDs are typically not practical for the study of single electron properties.

→ **Control the number and position of the QDs.**

Pictures from our e-beam lithography system



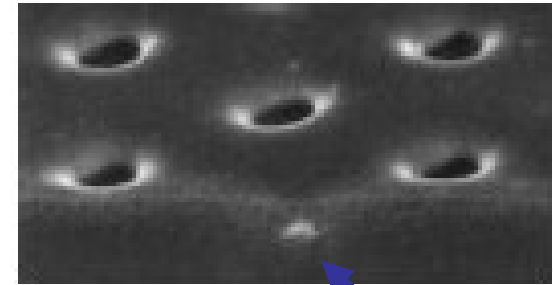
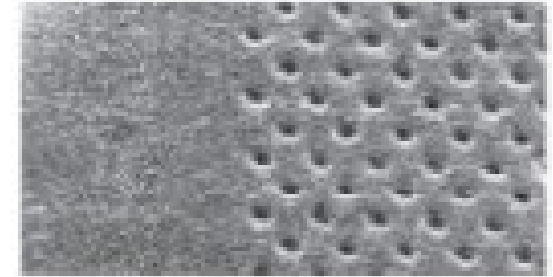
## Level 1-Growth:

Growth of high mobility 2DEGs on the basis of AlGaAs/GaAs.

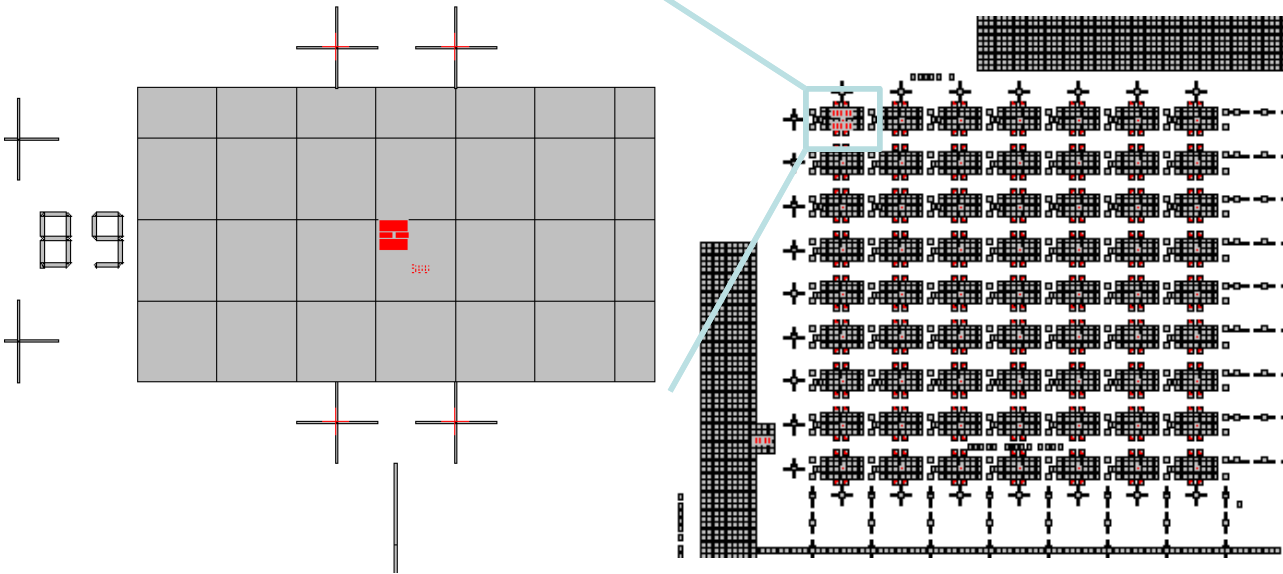
## Level 2-Mesa definition:

Optical lithography and wet chemical etching of mesas with a depth of 500 nm – 1000 nm.-> 4 blocks with **63** possible structures

## Electron microscopy images



InAs



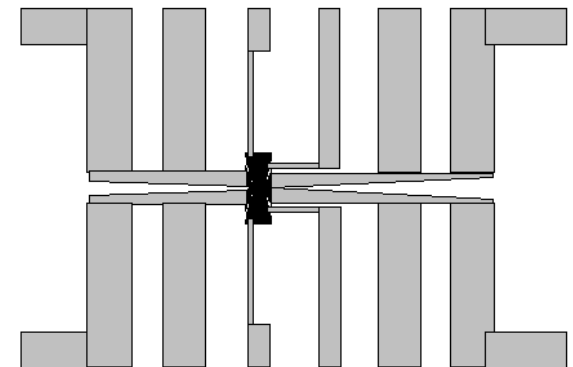
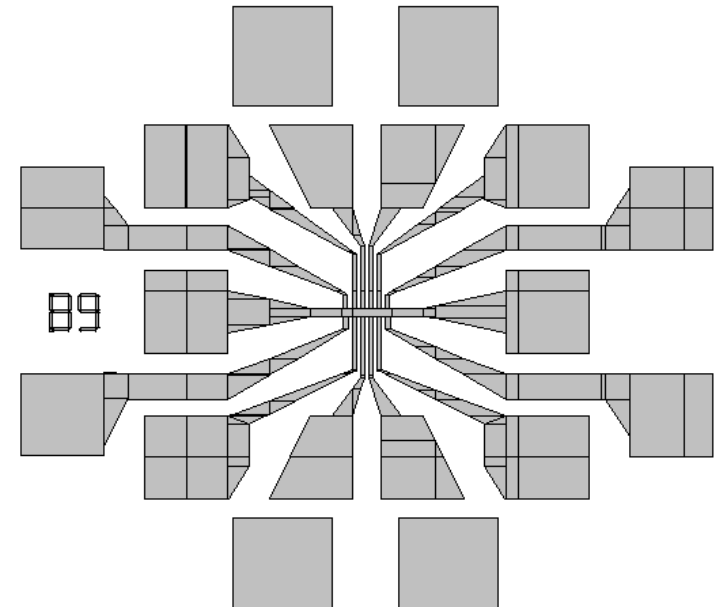
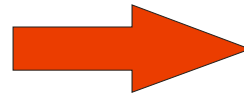
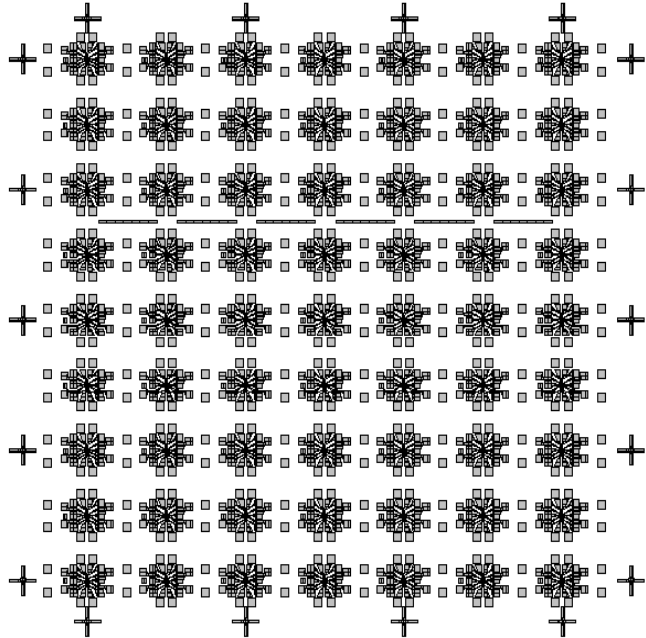
### Level 3 – Nanoholes:

- 1) 100 nm PMMA. 2) E-beam lithography (periods from 200 to 400 nm).
- 3) Develop the resists. 4) Dry chemical etching.

### Level 4 - Overgrowth process:

Overgrowth process with InAs and GaAs





## Level 5 – Hallbars:

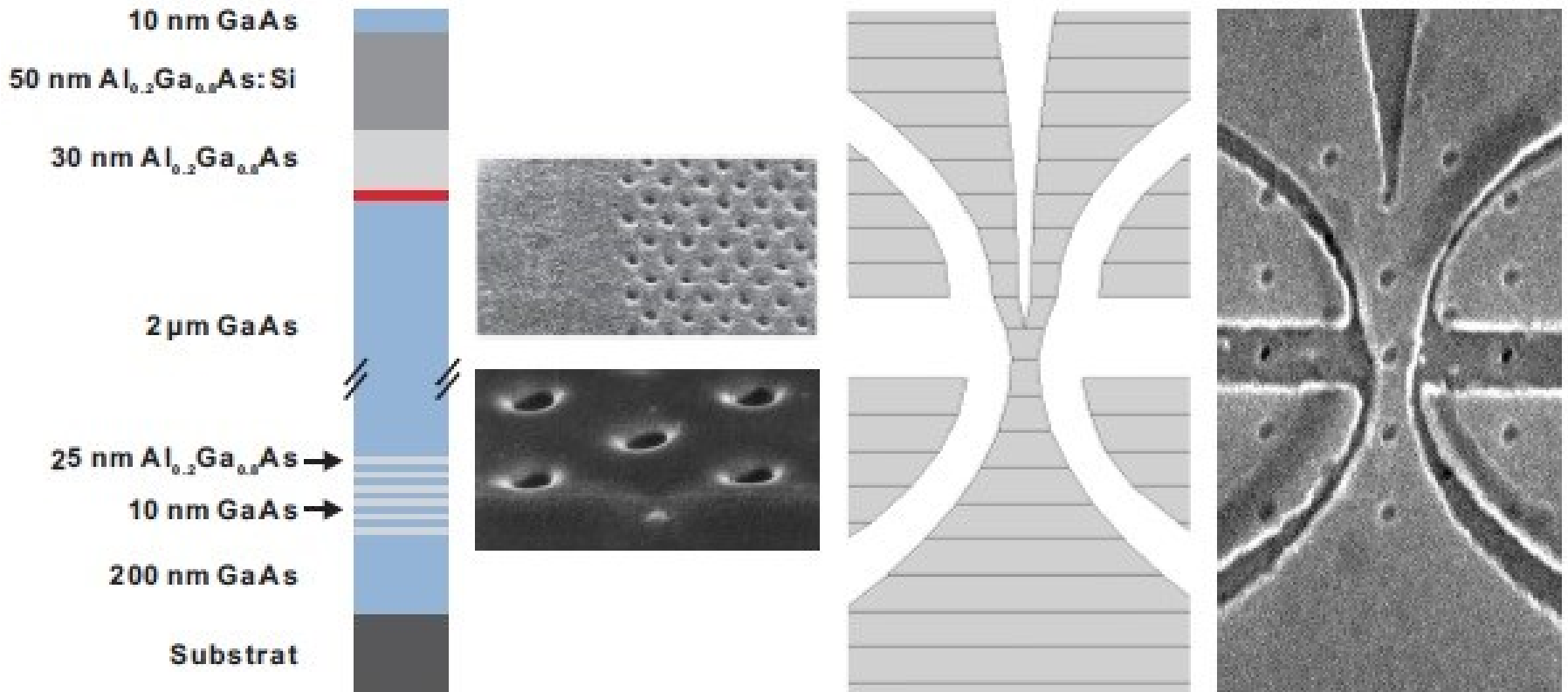
Optical lithography and wet chemical etching.

## Level 6 – Contacts:

Evaporate the contacts (AuGe/Ni/Au)

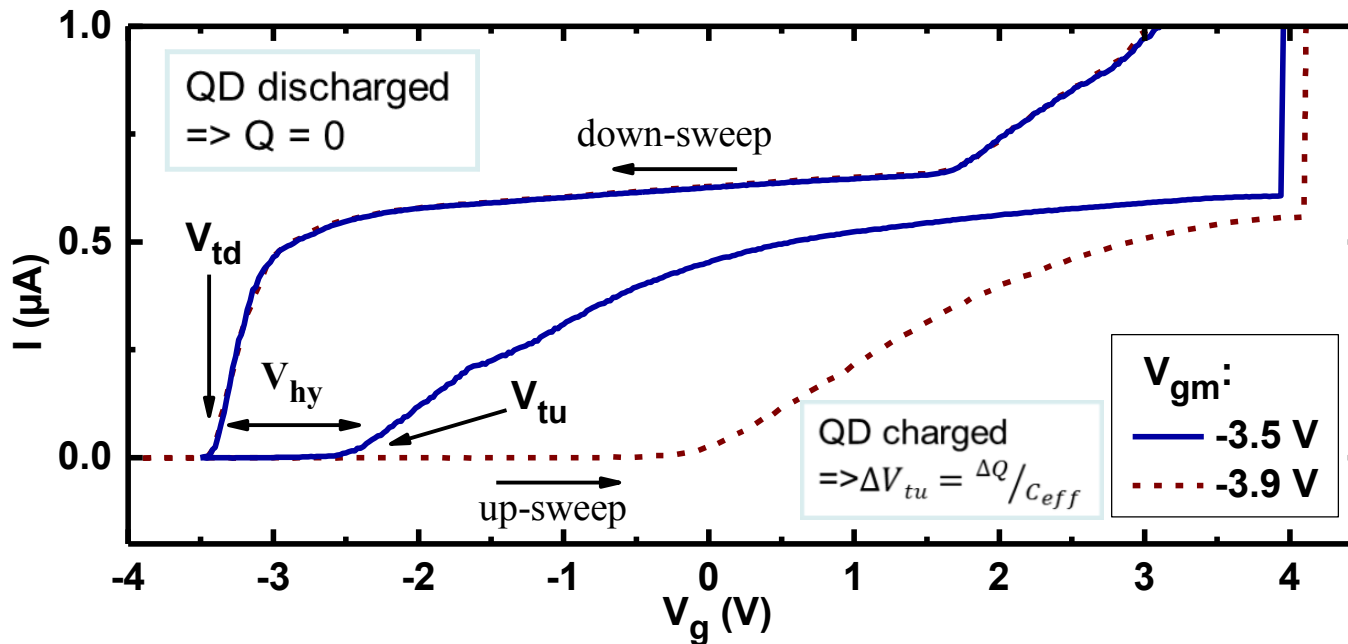
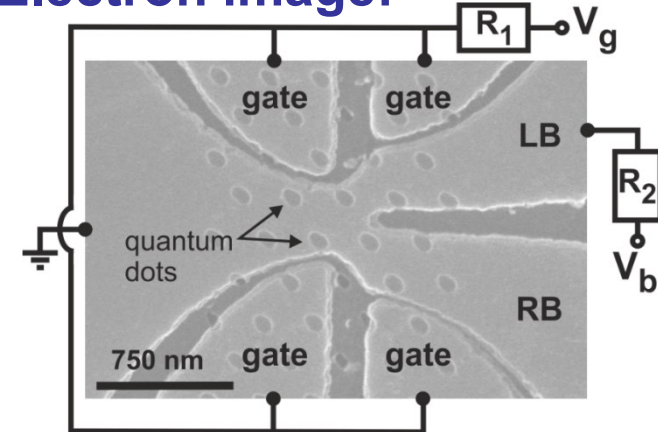
## Level 7 - Y-branch:

E-beam lithography and dry chemical etching

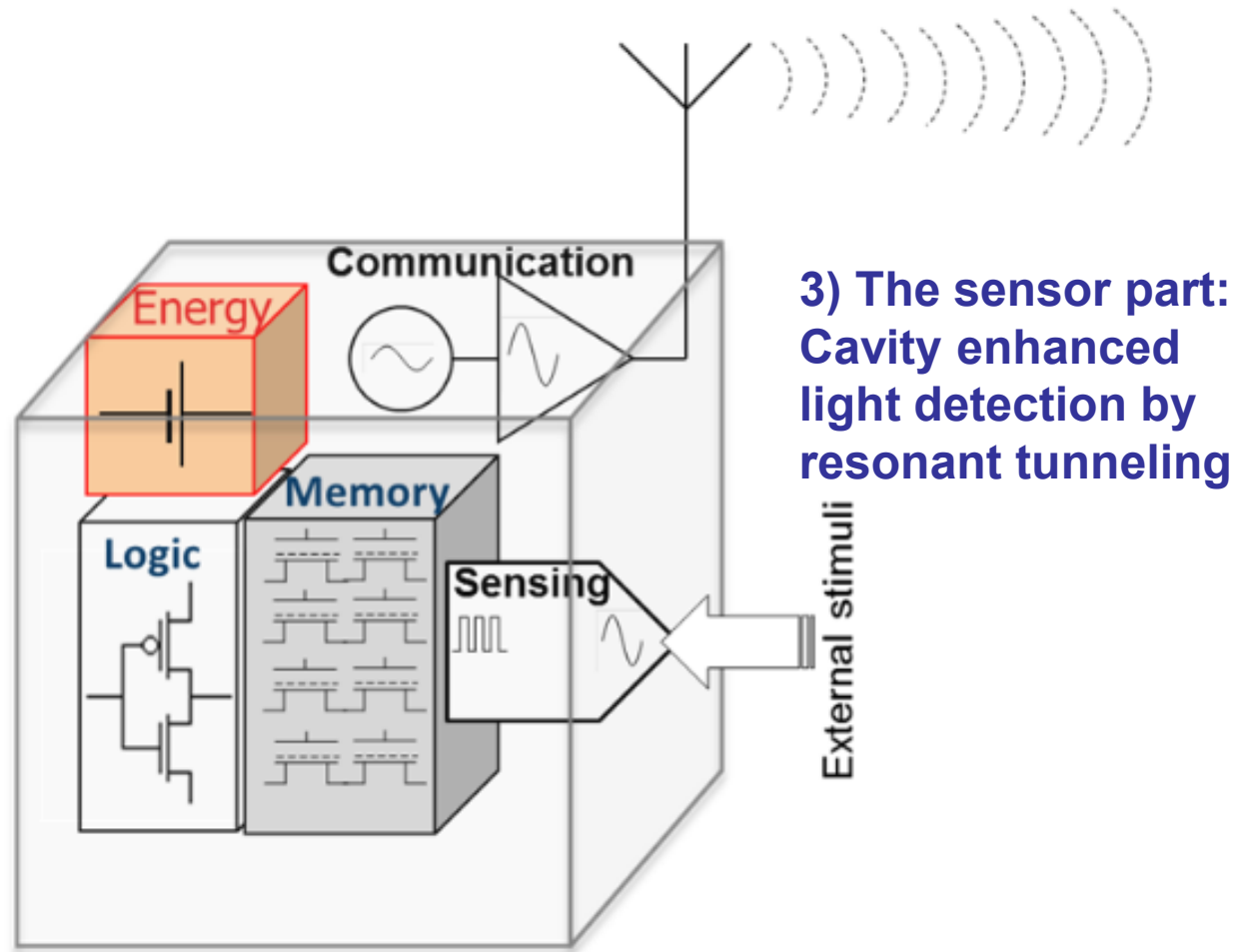


- $I(V_g)$ -characteristics for two charging voltages.
- Trace during down-sweep remains unaltered.
- $V_{tu}$  shifts towards larger values when decreasing  $V_{gm}$ .

## Electron image:



$$V_{hy} = V_{tu} - V_{td}$$



## Photocurrent:

$$\Delta I = \eta \cdot SE \cdot M \cdot P$$

$$SE = \frac{e\lambda}{hc}$$

## Sensitivity:

$$S = \frac{\partial \Delta I(V, \lambda)}{\partial P}$$

InGaAs: APD  $\sim 10$  A/W

Gain = 10

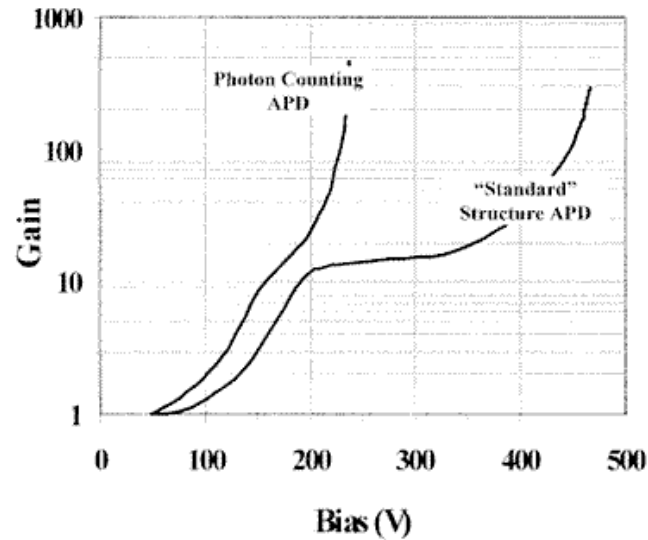
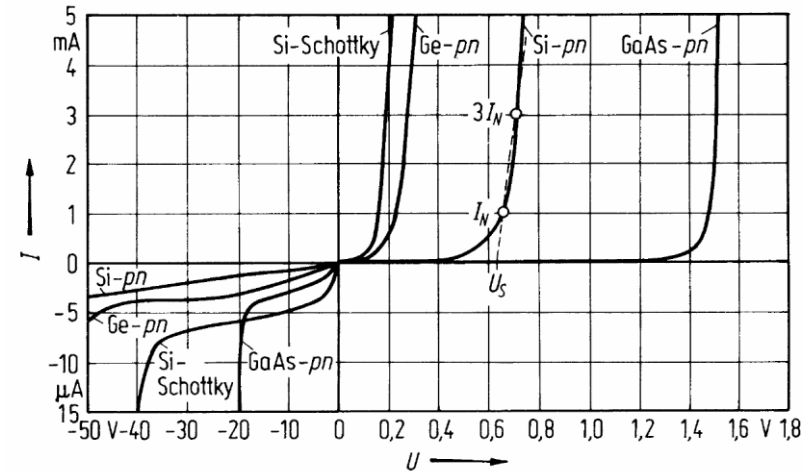
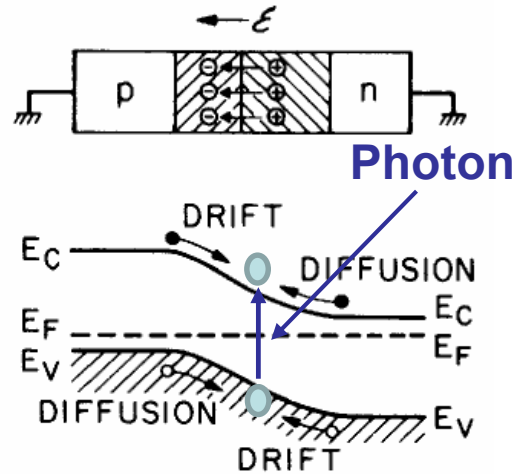
## But, noise:

$$i_{APD} \propto M, I_{dark}$$

$P$  = light power;  $M$  = gain

$SE$  = spectral response

$\eta$  = Quantum efficiency



## RTD light detection with embedded quantum dots:

- GaAs or InGaAs based RTDs with InAs quantum dots.
- Single-photon detection for light in the visible and IR wavelength region at  $\sim 4\text{K}$ .

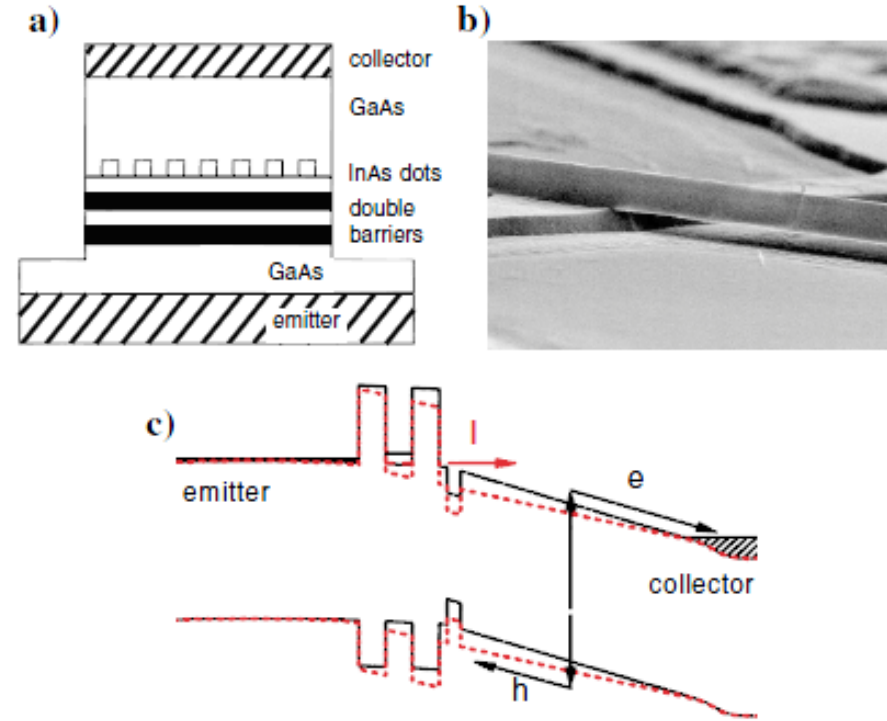
### Pros:

- It works!!
- Single photon resolution even for IR.

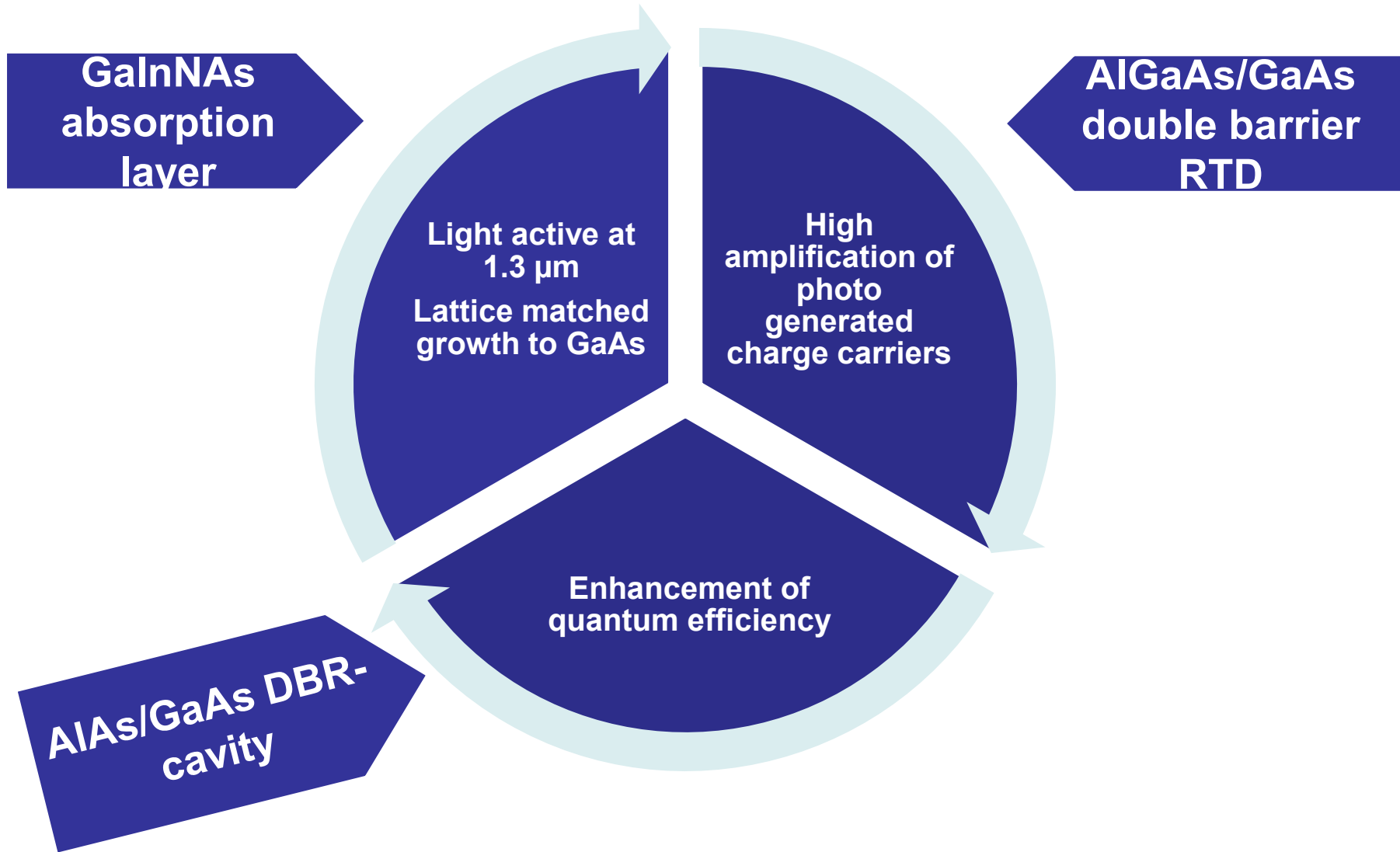
### Cons:

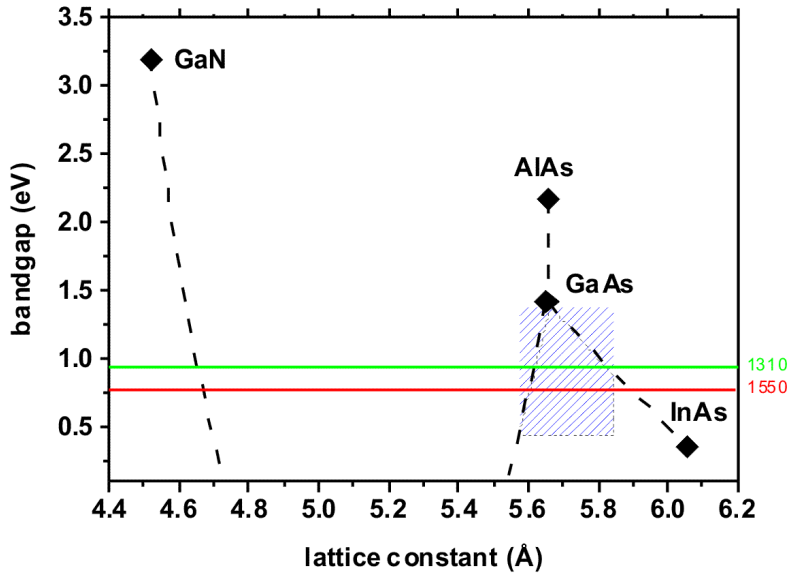
- InP wafer for  $1.3\ \mu\text{m}$   $\rightarrow$  expensive.
- Cryogenic temperatures.

J. C. Blakesley, et al. ,PRL **94**, 067401 (2005)



$\rightarrow$  Light sensing with RTDs at telecommunication wavelengths: **1.31** and **1.55  $\mu\text{m}$** .





- Band gap energy of GaInNAs depends on the In and N contents.

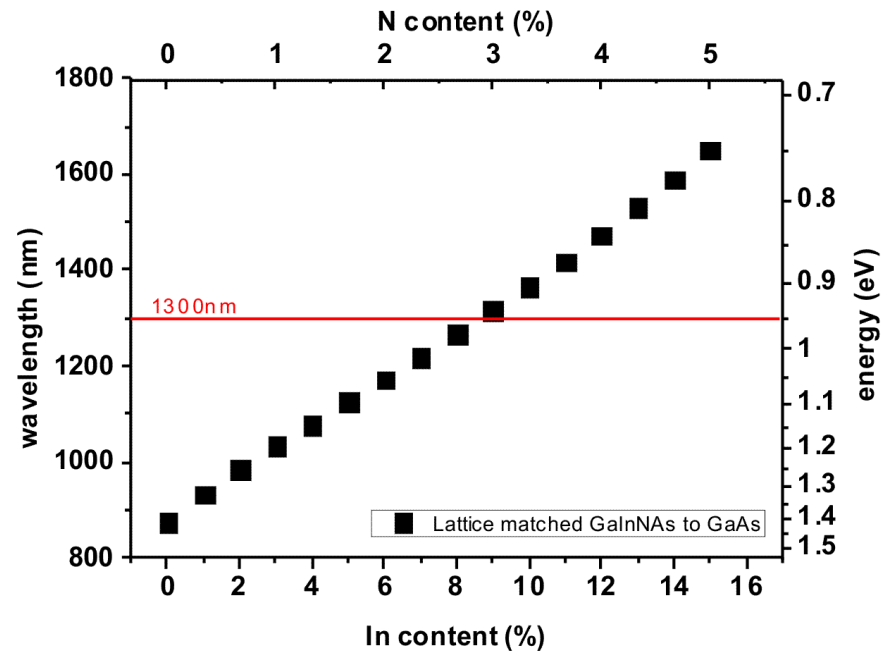
- For lattice matched growth on GaAs:

$$\text{In}[\%]/\text{N}[\%] \sim 3$$

- For 1.3  $\mu\text{m}$ :

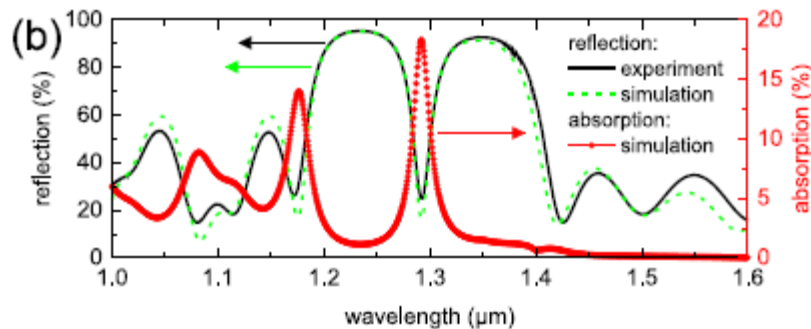
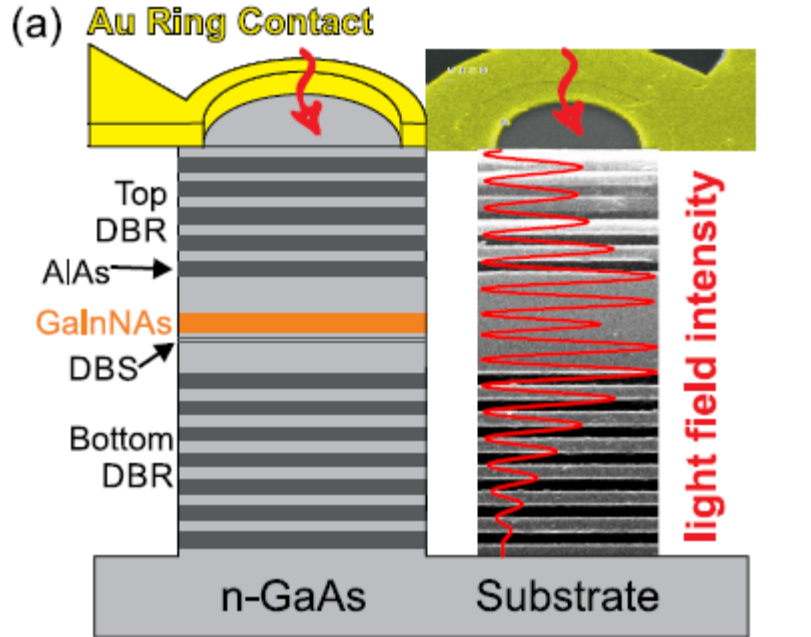


- Dashed lines correspond to the ternary materials e.g. InGaAs
- Blue shaded: Realizable area of GaInNAs



Kudrawiec *et al.*, J. Appl. Phys. 101, 023522 (2007).





## Sample Design:

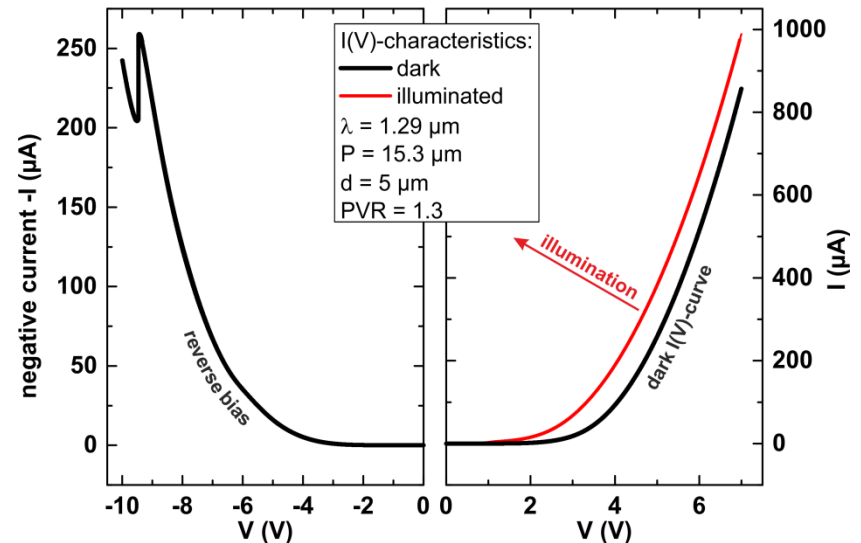
- Cavity consists of **5/7 GaAs/AlAs DBR mirror pairs**, with width of  $2\lambda$ .

## DBR-Properties:

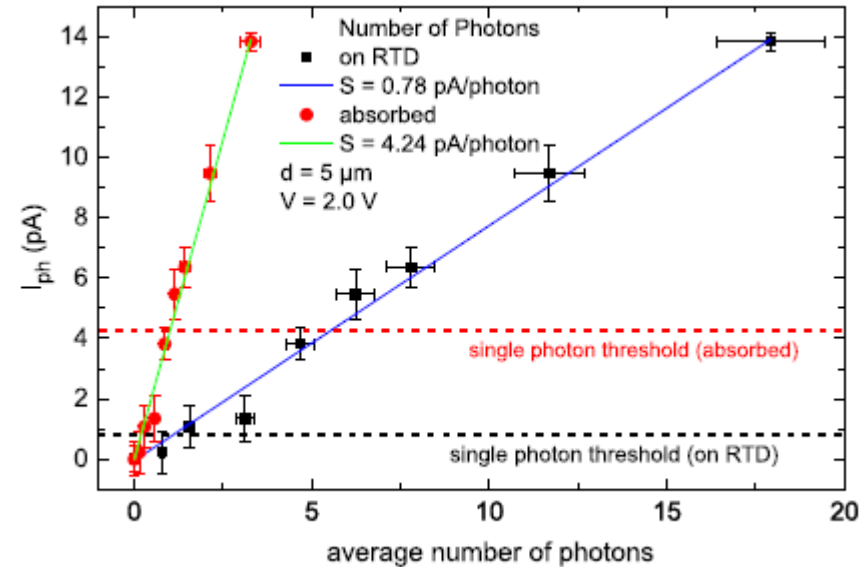
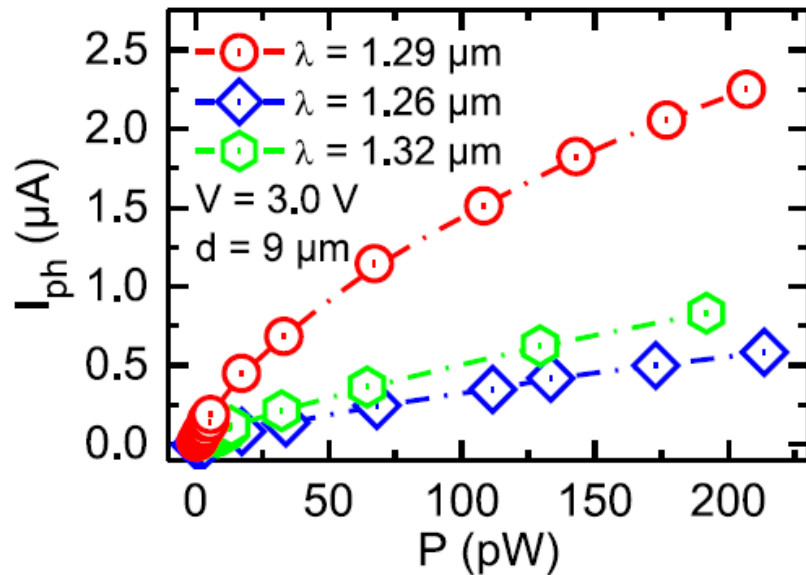
- Resonance  $\lambda = 1.29 \mu\text{m}$
- Quality factor  $Q = 50$

## Electrical-Properties:

- Peak-to-Valley Ratio  $PVR = 1.3$
- I(V)-shift under illumination
- No hole accumulation for reverse bias



A. Pfenning et al., Appl. Phys. Lett. 104, 101109 (2014)



## CW-Measurements:

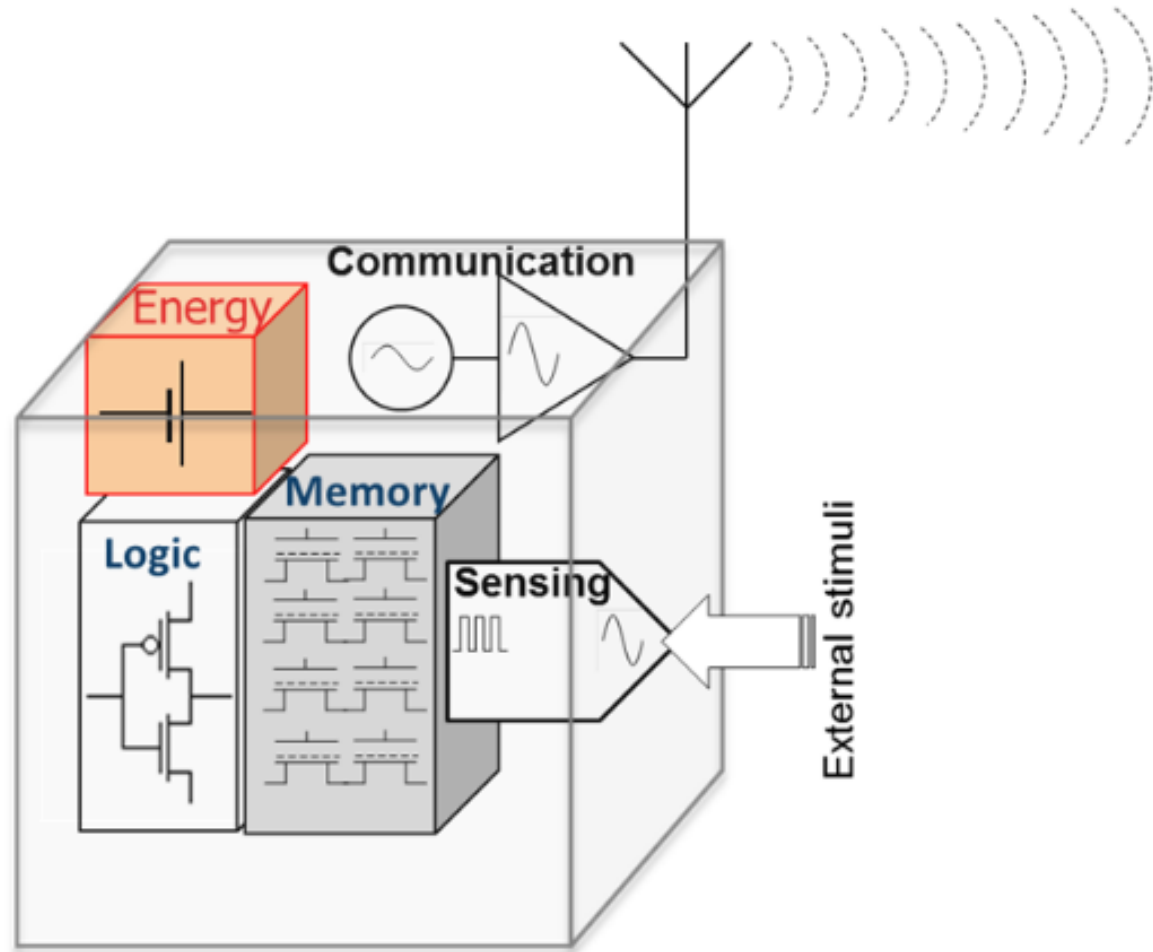
- Small signal linear fit:  
 $S(1.29 \mu m) = 31.2 kA W^{-1}$   
 $S(1.26 \mu m) = 2.90 kA W^{-1}$   
 $S(1.32 \mu m) = 5.89 kA W^{-1}$
- Enhancement of a factor **11** and **5!**

## Pulsed Excitation:

- For a single photon:  

$$I_{ph} = (779 \pm 15) fA photon^{-1}$$
- Single Photon Detection possible!**

## 4) The energy source part: Voltage fluctuation to current conversion



## Theory developed by:

- Rafael Sánchez, and Markus Büttiker: “Optimal energy quanta to current conversion.” Phys. Rev. B 104, 076801 (2011).
- Björn Sothmann, Rafael Sánchez, Andrew N. Jordan and Markus Büttiker “Rectification of thermal fluctuations in a chaotic cavity heat engine.” Phys. Rev. B 85, 205301 (2012).

*Sánchez et al.*

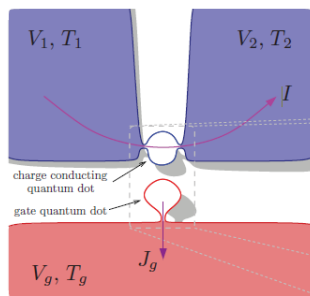
### Coulomb blockade regime:

Quanta relation:

$$\frac{I}{q} = \frac{J_g}{E_C}$$

Efficiency:

$$\eta(V_0) = \eta_c$$



*Sothmann et al.*

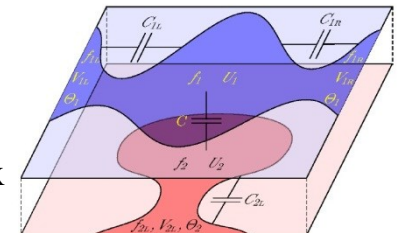
### Chaotic cavity regime:

Maximum power:

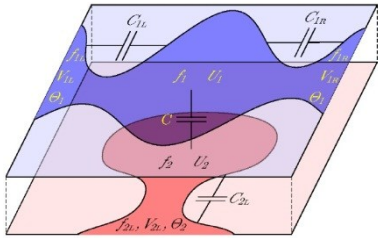
$$P_{max} = \frac{\Lambda^2}{4G_1\tau_{RC}^2} (k_B(\Theta_1 - \Theta_2))^2$$

Efficiency:

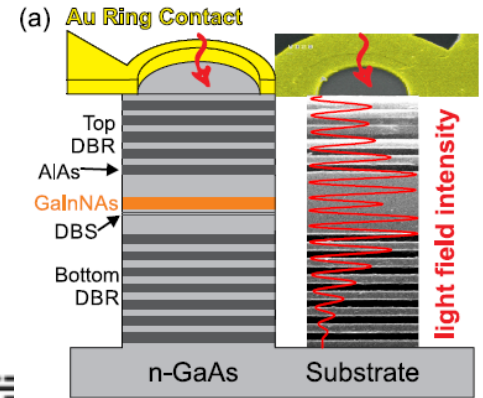
$$\eta_{max} @ P_{max}$$



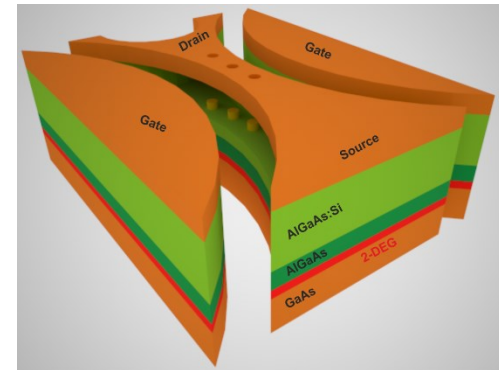
**Coupled QD system =  
Efficient heat engine**



**Cavity enhanced light  
detection by resonant  
tunneling**



**QD flash  
memory**



**Universal and  
reconfigurable  
logic gates**

